Coated Conductor Development Roadmapping Workshop II

Bridging the Gap Between Tape Fabrication and Cable Manufacturing to Meet Customer Needs

Workshop Proceedings

Loews L'Enfant Plaza Hotel Washington, DC July 28-29, 2003

Superconductivity for Electric Systems Program

Office of Electric Transmission and Distribution U.S. Department of Energy

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Coated Conductor Development Roadmapping Workshop II Bridging the Gap Between Tape Fabrication and Cable Manufacturing to Meet Customer Needs

I. SUMMARY

I.I Background and Purpose

In January 2001, the U.S. Department of Energy held a two-day facilitated workshop aimed at defining a future research agenda to evaluate, demonstrate, and accelerate processing, fabrication, and manufacturing of high-temperature superconducting (HTS) coated conductors that would meet the needs of the U.S. electric power industry. This workshop resulted in the Coated Conductor Technology Development Roadmap: Priority Research and Development Activities Leading to Economical Commercial Manufacturing, August 2001, (see www.ornl.gov/HTS/pdf/CCRoadmap8-23.PDF). The roadmap updates the November 1997 report, Research and Development Roadmap to Achieve Electrical Wire Advancements from Superconducting Coatings.

The 2001 roadmap presents the priority R&D needs in the following activity areas:

- Fabrication Pathways
- Substrate Development and Characterization
- Simplified Buffer Layer Architecture
- Improved YBCO Quality
- Faster Deposition Rates
- Process Monitoring and Control Strategies/Methods
- Production Scale-Up
- End-User Applications

The 2001 roadmap considers the time period of 2001 through 2005. *Performance targets* (at 77K) developed at the workshop are as follows:

2001:	1m; J_c (end-to-end) = 1 MA/cm ² ; I_c (end-to-end) = 50 A/cm-width; throughput (1 cm-wide) = 20 m/hr
2003:	10 m; 50 A/cm-width 1 m; 100 A/cm-width
2005:	1 km; $J_c = 1 \text{ MA/cm}^2$; $J_e = 5-10 \times 10^4 \text{ A/cm}^2$; 50µ thick substrate; 100 m/hr throughput
2006:	Deployment of power products using new wire
2007:	>km lengths; 1000 A/cm-width
2010:	Wire cost reduced to \$10/kA-m

The highest priorities identified are: increasing HTS film thickness while maintaining high current density and increasing film deposition rates or mass throughput while maintaining quality.

Roadmap targets for 2005 are:

- Accelerate Development of Existing Fabrication Technology
- Develop New Approaches/Alternative Fabrication Techniques
- Substrate Development and Characterization
 - Substrate cost \$1/m, stronger, thinner, non-magnetic
 - Continuous texturing systems, >100m lengths
 - On-line diagnostics before HTS deposition
- Simplified Buffer Layer Architecture
 - Non-vacuum processing
 - No buffer approaches
 - Dual side coatings
- Improved YBCO Quality
 - Defects and causes
 - Current limiting mechanisms >1 km
 - 500 A/cm-width (77K, self-field)
- Faster Deposition Rates
 - Enhance PLD and other vapor deposition process efficiency by 5-10 $\rm X$
 - Rate: 100m/hr/1 cm-width; \geq 500A

In late October 2002, a German research group reported that they had produced a 10 m IBAD-YSZ tape with a $J_c = 2.23$ MA/cm², I_c (end-to-end) = 223 A/cm-width (at 77K). These tapes were prepared on a 50-100 micron nonmagnetic stainless steel ribbon, using a textured YSZ, IBAD buffer layer (1.3-1.5 micron thick), 1-3 micron layer of YBCO, and a gold protective layer. They employed a high-rate PLD process, with volumetric coating rates of 60-70 nm-m²/hr.

In early December 2002, U.S. companies reported that they had exceeded the DOE goals. SuperPower achieved I_c values above 100 A/cm-width end-to-end for a 10 m tape at 77K produced by the IBAD-MOCVD tape process. American Superconductor also achieved I_c values above 100 A/cm-width end-to-end for a 10 m tape using RABiTS-MOD (BaF₂) process. These accomplishments exceeded the DOE December 2003 performance targets. This accelerated progress has made it necessary to revisit and update the 2001 roadmap.

DOE is now starting the process of developing a new roadmap that builds on prior efforts and incorporates the latest achievements in **continuous processing of HTS coated conductors.** This new roadmap will focus on defining R&D priorities and pathways to achieve the vision of a commercially suitable final conductor configuration and assembly. New ways will be explored for the national laboratories, academia, and

private companies to work directly together to accelerate technology transfer and product development. In this technology roadmapping workshop, you will help identify the R&D activities, priorities, and pathways for achieving the Vision.

The efforts of this workshop will result in the new *HTS Coated Conductor Development Roadmap* that will link the broadly defined targets outlined in the vision with a detailed research agenda of near- and mid-term R&D activities addressing technology needs of the electric power industry. When the roadmap is published, implementation through collaborative research partnerships composed of private companies, government agencies, academia , and private research institutions will help the *Vision* become reality.

I.2 Vision

Low-cost, high-performance HTS Coated Conductors will be available in 2005 in hundreds of meter lengths. For applications in liquid nitrogen, the wire price will be less than \$50/kA-m, while for applications requiring cooling to temperatures of 20-60K the price will be less than \$30/kA-m. By 2010, the priceperformance ratio will have improved for kilometer lengths by at least a factor of five.

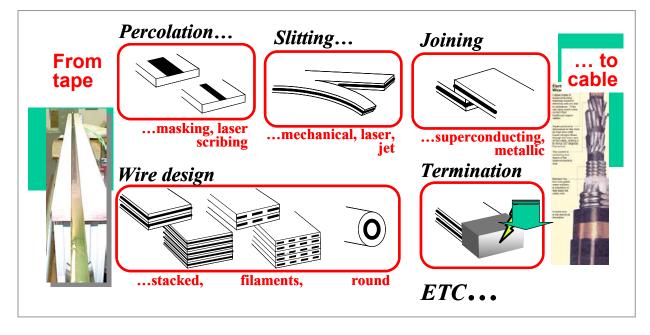
HTS wires based upon coatings of YBCO on textured, buffered metallic substrates will offer unprecedented current carrying capacity at high temperatures and in the presence of strong magnetic fields. Coated conductors also will be fabricated using industry scalable deposition technologies, many of which are presently in use in the semiconductor and photographic film industries, but which have not been adapted for use in **continuous processing** of the templates or superconductor layers.

The HTS industry will work with national laboratories to develop high-performance, low-cost, HTS coated conductor wire. Specific national laboratories have developed cutting edge research facilities where industry researchers can work collaboratively with national laboratory scientists. This partnering arrangement is designed to accelerate development and private sector application of HTS coated conductor wires. These partnerships will also enable faster scale-up of discoveries in materials laboratory processes that give unprecedented ability to carry large electric currents. A performance measure is achieving industry production of kilometer lengths of HTS coated conductor wire by 2010. Beyond this, present work will focus on cooperative national laboratory/private company research intended to reproducibly fabricate 100meter lengths of wire that carry over 300 amps in single strands.

The U.S. will maintain its leadership position in HTS coated conductor development. U.S. industry will apply HTS devices to address critical issues in the nation's long-term energy strategy.

1.3 Conductor Design and Engineering Issues

This workshop focused on bridging the gap between tape fabrication and cable manufacturing.



Workshop participants were asked to identify and discuss HTS conductor design and engineering activities between now and 2010. These activities will form R&D pathways that will ultimately:

- Resolve issues limiting application of today's HTS industry-manufactured coated conductor by developing a detailed understanding of materials properties and limitations relevant to specific applications
- Reduce the alternating current losses in half compared with today's geometry
- Demonstrate commercial availability, through U.S. industry partners, of coated conductors in forms engineered for magnets and cables
- Develop conductor and "building block" designs that will enable full implementation with HTS cables, transformers, and generators
- Integrate engineered conductors with balance of system cryogenics, electronics.

Initial coated conductor design and engineering issues are:

- Adhesion of coatings at low temperature
- Cross-sectional architecture for reinforcing tapes
- All tape mechanical properties unknown except longitudinal tension
- All epoxy-impregnated coil properties unknown
- Splicing method and properties of splices not known
- Slitting methods and properties of substrates and YBCO conductors not known
- Shock tolerance and strain rate effects not known

- Long-term performance (degradation over time) not known
- Coil dynamic testing capability needed
- Definition and basic modeling of "building block" characteristics needed

It is clear that a strong coordinated effort is needed to overcome the barriers to continuous processing of high quality, low cost HTS coated conductors and production scale-up that will lead to industrial-scale commercial manufacturing.

I.4 Workshop Format and Agenda

The workshop was a 1½ day facilitated meeting that took place July 28-29, 2003 at the Loew L'Enfant Plaza Hotel in Washington, DC. The workshop brought together respected experts from various segments of the industry and others that are involved in developing processes to fabricate finished wire products and devices using advanced HTS materials. Invited participants represented a cross-section of companies that produce HTS wire as well as companies that are likely to use HTS wire, researchers, and government programs. The workshop focused on technical solutions to major material and processing challenges. It included a plenary session, facilitated working sessions, and a summary session. The Agenda can be found at the end of this section.

During the breakout sessions, each group was asked to review the technical barriers and select the most critical challenges to achieving the vision. Participants were asked to share their thoughts on what the "final" conductor configurations should look like in order to satisfy the vision. This will help to define the final conductor as the goal of the roadmap. Participants identified and ranked needed R&D activities. These activities were categorized as near- and mid-term time frames and linked as appropriate (e.g., R&D that must be completed before other R&D can begin). For the high-priority R&D activities, the appropriate role of the national laboratories, private companies, and universities were discussed.

Specific Workshop Objectives

- Assess the performance goals for the various components of coated conductors, i.e., the metallic substrate, buffer layers, YBCO coating, and any additional components needed for stable conductor operation.
- Develop a consensus of the critical research needs and determine the improvements needed for processing methods to meet performance goals.
- Focus on solving "problems" that slow progress toward meeting the performance goals and identify opportunities for cooperation between industry and government.
- Define pathways to transform coated conductors from laboratory-scale development to real-world commercial conductors. Identify key opportunities to scale-up existing coated conductor technology to commercially-attractive manufacturing processes.

COATED CONDUCTOR TECHNOLOGY DEVELOPMENT ROADMAP II

BRIDGING THE GAP BETWEEN TAPE FABRICATION AND CABLE MANUFACTURING TO MEET CUSTOMER NEEDS

FINAL AGENDA

Loews L'Enfant Plaza, Washington, DC

MONDAY, JULY 28, 2003

Тіме	SESSION
7:30 – 8:30 am	Registration and Continental Breakfast
8:30 – 10:30 am	 Plenary Session Welcome & Introduction – J. Daley, DOE Vision Thought Provoking Perspectives on HTS Coated Conductor Product Needs David Larbalestier, U of Wisconsin, Madison John Scudiere, AMSC Venkat Selvamanickman, SuperPower Ken Marken, OST David Lindsay, ULTERA Workshop Process and Expectations – J. Badin, Energetics
10:30 – 11:00 am	Break
11:00 – 12:00 pm	Plenary Session (continued)
12:00 – 1:15 pm	Luncheon
1:15 – 5:30 pm	 Breakout Sessions Defining the Vision-Achieving Conductor Break (3:00 - 3:30 pm) R&D Activities to Achieve the Vision
6:00 pm	Reception

TUESDAY, JULY 29, 2003

Тіме	SESSION
7:30 – 8:00 am	Continental Breakfast
8:00 – 10:30 am	Breakout Sessions (continued) - Actions and Timeframes
10:30 - 10:45 am	Break
10:45 – 12:00 pm	Plenary Summary Session - Findings of Breakout Sessions and Concluding Remarks
12:00 pm	Adjourn

1.5 What Comes Next?

The focus of the workshop was on continuous processing and manufacturing scale-up of HTS coated conductors. The results of this workshop will help establish a comprehensive technology agenda that will be used to guide future research initiatives and partnerships. Discussions covered a wide spectrum of non-proprietary research needs and opportunities. Some research may be best pursued by equipment developers and manufacturers, some is appropriate for industry collaborations with universities, and some is best suited for industry-government partnerships. Participants were encouraged to seek new opportunities for R&D collaboration. Creative ideas were sought.

The results of the workshop will be used to:

- Revise performance targets for each government fiscal year beginning with 2004
- Confirm or modify critical material and processing challenges and limitations to achieving the vision for continuous processing of HTS coated conductors
- Identify key opportunities to scale-up existing coated conductor technology to commercially-attractive manufacturing processes
- Reach a consensus of the priority research needs
- Develop near- and mid-term R&D activities
- Identify interrelationships between R&D activities
- Make recommendations for an optimum R&D portfolio
- Identify opportunities for cooperation among the industry, academia, and the government to overcome key materials and process related challenges.

The efforts of this workshop will result in an updated *HTS Coated Conductor Development Roadmap* that will link the broadly defined targets outlined in the vision with a detailed research agenda of short-, mid-, and long-term R&D activities addressing technology needs of the electric power industry. When the roadmap is published, implementation through collaborative research partnerships composed of private companies, government agencies, academia, and private research institutions will help the *Vision* become a reality.

2. DISCUSSION GROUPS

2.1 Organization and Focus Questions

The workshop was designed as a product-oriented meeting in which participants have active roles. The four breakout sessions consisted of:

- 1. Substrates/Buffers
- 2. RE-123 Nucleation, Growth, and Flux Pinning
- **3&4** Conductor Design and Engineering (A&B) (ac losses, stability, quench protection, conductor geometry, cost-effective manufacturing)

Breakout sessions 3 and 4 covered the same scope and were held concurrently. The outcome of this workshop was to identify the most critical issues and activities for an R&D program that will develop and transfer successful coated conductor technologies. We also hoped to identify novel approaches that if successful would have revolutionary impact.

Breakout Group 1: Substrates/Buffers

Fabrication of a coated conductor requires an integrated material system including the substrate, buffer/template layer and superconductor. This integrated system must achieve a microstructure that leads to the necessary superconducting performance. Deposition approaches capable of achieving such integrated systems at an economical cost must be developed to meet a variety of expected coated conductor applications. While remarkable success has been achieved recently, basic material science studies will be necessary to create optimized buffer/template layers and optimized, tailored conductors. Specific issues include surface finish requirements, strength and magnetism, process speed, and stress-related issues. Participants considered the following:

- What would be the most difficult aspect of the process to scale-up to long lengths of 100 m?
- What would be the most difficult aspect of the process to scale-up to widths of several centimeters followed at some point in the processing by a slitting operation?
- What R&D areas do you think need to be pursued to make this technology viable?

Breakout Group 2: RE-123 Nucleation, Growth, and Flux Pinning

Various approaches to the growth of the superconducting layer in a coated conductor have been demonstrated. This has occurred, however, on the basis of a limited understanding of the growth mechanism and phase stability of the YBCO conductor. Optimization of the superconductor for the various applications will require a firm understanding of how to develop the needed microstructure consistent with economical, well controlled growth processes. Uniformity and reproducibility of superconducting properties in coated conductors need to be achieved. Specific issues include:

- What controls the microstructure?
- What are the effects of high deposition rates?
- Do liquid fluxes play a role in the YBCO growth?
- What chemical additions or substitutions in YBCO might be beneficial?
- Effect of the interface with the epi-buffer layer on the YBCO?
- How can we achieve the needed level of deposition control?
- The properties of YBCO dependent on the deposition process/method?

Flux pinning in coated conductors has been one of the major thrusts of coated conductors research because most projected applications, both dc and ac, are in magnetic fields. Research is needed on optimizing the flux pinning properties of coated conductors by practical methods. Specific issues include:

- How do intra-grain and inter-grain flux pinning defects affect J_c vs. thickness in coated conductors?
- How do we develop mechanisms and methods to improve intra-grain and intergrain flux pinning structure?

Breakout Groups 3 & 4: Conductor Design and Engineering

The ultimate architecture of the HTS coated conductor will be determined by various requirements, not all of which are capable of simultaneous optimization. Coated conductors must be protected at local hot spots and for magnet quenches, meaning that both the local YBCO-stabilizer interface resistance and the total parallel conductance of the stabilizer are important. Means to minimize hysteretic losses are important for ac applications and since many of these involve subdivision of the coated conductor, the issue of percolation through the network of barriers within the YBCO is important. For magnet applications the whole angular dependence of the critical current is important because all orientations of the conductor are also important, suggesting that architectures that put the YBCO close to the neutral axis are favored. Specific issue include: ac losses; stability; quench protection; conductor geometry; and cost-effective manufacturing. Participants should also considered factors such as tape dimensions, geometry, operating conditions, cost, length of single pieces, amperage, and other electrical, mechanical, and magnetic properties for electric power applications.

The following focus questions were posed within each concurrent breakout group:

- What are the most critical technical developments needed to achieve the conductor envisioned in 2010?
- For the top technical developments, what are their status, targets (2005, 2010), and gaps?
- What R&D activities are needed to achieve the vision?
- For the top R&D activities, what are the interim milestones, performers and linkages?

2.2 Discussion Group I: Substrates/Buffers

Performance Characteristics

Increasing substrate strength can allow the thickness of the substrate to be decreased and the overall fraction of conductor that is superconductor material to increase, thereby increasing Je. Specific targets included an absolute minimum substrate and buffer strength of 100 MPa, with 200 MPa being more reasonable. In the final HTS coated conductor, achieving 20% of total conductor mass being superconductor is another way to think about this area.

In 2010, substrates will be produced by high-yield processes, possibly through increased width and slitting. In some processes, such as RABiTS, slitting tape could hinder grain size; controlling grain size and grain aspect ratio may help to alleviate these problems and

Participants:							
Substrates and Buffers							
NAME	ORGANIZATION						
Paul Berdahl	Lawrence Berkeley National Laboratory						
Claudia Cantoni	Oak Ridge National Laboratory						
Najib Cheggour	National Institute of Standards and Technology – Boulder						
David Christen*	Oak Ridge National Laboratory						
Stephen Dorris	Argonne National Laboratory						
Eric Hellstrom	Applied Superconductivity Center University of Wisconsin						
Dirk Isfort	Nexans SuperConductors						
Dominic Lee	Oak Ridge National Laboratory						
Vic Maroni	Argonne National Laboratory						
Marshall Reed	U.S. Department of Energy						
Kamel Salama	University of Houston						
Shara Shoup	MicroCoating Technologies						
Xuming Xiong	SuperPower, Incorporated						
* Report Out Presenter							
FACILITATOR: ROSS BRINDLE, ENERGETICS, INCORPORATED							

potentially allow higher I_c . Process speed may be more accurately measured in terms of volume per unit time rather than length per unit time. Substrates should be non-magnetic.

There will be a significant effort to reduce the complexity of buffer systems. Buffer systems will be used that provide adequate oxygen and cation diffusion barriers but transmit epitaxy and that can be produced at greater thicknesses without cracking, thereby reducing the number of layers and, consequently, their complexity and cost. Conductive buffer layers, single-layer buffers, or possibly eliminating the need for a buffer layer at all are all advanced concepts that buffer materials may enable.

Consistent, reproducible texture control, to below 5° (possibly 2°) will be used to achieve the cost points outlined in the vision. At 5° , effects are seen in the buffer and substrate; achieving 2° will allow some flexibility during processing.

By exploring ways to reduce the YBCO synthesis temperature down from 750 C to 600-700 C, greater buffer options may be enabled. Finally, the 1/m of substrate goal that was outlined in the previous roadmap edition remains a valid and worthy goal today.

Summary slide points:

- Consistently produce long lengths (>500 m) of complete substrate with buffer layer with good properties
- Simplify architecture by reducing number of layers (to drive cost down)

- $\bullet~$ To increase $J_{\rm e},$ several options should be explored (double-sided buffers, conductive substrates)
- Substrates should be non-magnetic, preferably conductive
- Bottom line: buffers and substrates are capable of sustaining high J_c

Key Breakthroughs

The breakthroughs that will allow the vision to be realized are grouped into three basic areas:

- Improved Theoretical Understanding
- New Processes For Enhanced Performance
- Scale-Up (Length and Width)

By achieving a more complete basic understanding of texture development and the effect of impurities, granularity, and sulfur superstructure, researchers can more effectively manage substrate textures. Similarly for buffers, understanding how self-planarization and improved texture is achieved by SrRuO3 may lead to new buffers with even better textures. Understanding texturing mechanisms in both substrates and buffers can allow the creation of buffers with sharper texture than substrates. Finally, understanding how texture is affected by specific YBCO processes can lead to greater advances.

Breakthroughs to develop alternative processes that allow for greater process speeds, lower demands on the substrate, improved texture, smaller grains, improved surface finish, and higher yields are central to the vision. Breakthroughs in conductive substrates with high strengths (perhaps copper based) and possibly new geometries (such as round wires) can lead to new systems with improved performance and lower cost. Buffer development may include conducting buffers with low interfacial resistivity, uniform, solution-based single-layer buffers or double-sided buffers, ultimately leading to a "super buffer layer."

The key breakthrough that will allow scale-up of substrate and buffer production to lengths and widths that will achieve the vision cost goals is reliable process control that can sustain properties over long times.

Summary slide points:

- Basic understanding of texture development and effect of impurities
- Understanding of texturing process in relation to geometry
- Process control and feedback over long times
- Conductive buffers with low interfacial resistivity
- Single solution buffer, double-sided, 500A/cm I_c (to increase width)

R&D Activities

The R&D activities needed to achieve the breakthroughs needed for substrates and buffers to ultimately achieve the vision are organized in six general areas:

- Chemical and Physical Characterization
- Mechanical Characterization
- Understanding of Texturing
- Conductive Buffer Layers and Copper Alloy Substrates
- Process Control
- New Concepts

Characterization of substrates, buffers, and entire coated conductor systems will continue to play a central role in the R&D agenda for HTS coated conductors. Developing substrates that are chemically compatible with YBCO and can allow for the elimination of buffer layers can, if technically possible, reduce the overall system complexity and cost. Research on understanding diffusion dynamics through buffers and substrates will aid in materials and system development.

New concepts may offer promise for significant advances in capabilities and/or cost reduction, and R&D that investigates these concepts is crucial. Round wire systems and solution-based deposition techniques are identified as two areas of potential investigation.

Summary slide points:

- Research on diffusion dynamics through buffers and substrates
- Predictive modeling of stress states in the substrate
- Study and modeling of texture in relation to microstructure
- Modeling and experimental studies of deposition and texturing
- Nucleation and growth of "thick" solution buffers with uniform coverage
- Conductive buffers with good diffusion barrier and compatibility with YBCO
- Feedback process control

Take-Home Messages

- Lots of work to do!
- Substrates and buffer layers are the platform to HTS coated conductors they are critical pieces of the entire CC.
- Process control to obtain length and width is critical to cost-effective manufacture of substrates and buffers.
- Many of the other priorities described are aimed at improving substrate and buffer performance.
- Considering the vision time frame, working with other communities (e.g., process control industry) to accelerate development and scale up may be mandatory.
- Fundamental research and innovation is still strongly needed.

TABLE 2.2.1: CHARACTERISTICS AND FABRICATION OF SUBSTRATES AND BUFFERS IN THE 2010 HTS COATED CONDUCTOR

	Process Speed	SURFACE FINISH	Strength	MAGNETISM	New Materials	Optimization	BOTH BUFFERS AND SUBSTRATES (No Category)
Substrates			 Fraction of conductor with supercon- ductor in it should be high (~20%) Related to strength Stronger the better to reduce thickness and increase J_e (25 micron thickness) 	Non-magnetic	 Substrate material that meets vision is used (copper?); RABiTS currently too expensive (labor costs) Aspect ratio of grains can influence I_c – control aspect ratio in 2010 	 Thinner, wider substrates for increasing processing yield, lower costs RABITS – slitting tape could hinder grain size, in 2010 control grain size better 	 Texture control (2°?); lower affords more margin for error; ~5° is where effects are seen - Reproducibility Use homogeneous processes - parameters in substrate and buffer should not vary more than 5%
Substrates and Buffers	 ~25 m/n for 10 cm width Volume/time or volume/ width/time may be more accurate for comparisons across technologies 	 Roughness on order of 1 nm. (if buffer can be planarized, can tolerate more roughness) Closer to 15 nm for ISD 	 >100 MPa for substrate and buffer (lower limit, 200 MPa may be more practical) 		 Non-reactive to superconductor Substrate may be used as a stabilizer 	 Higher manufacturing yield Buffer material that is good cation and oxygen barrier but transmits epitaxy 	 Reproducibility Bring YBCO synthesis temperature down (from 750 to 700) to enable other buffer options \$1/m is good substrate cost target Thermal expansion may be an issue for some materials (e.g., Cu not as close to YBCO) This is effected by processing, problem in current substrates
Buffers					 Buffer is simple and thin (least number of layers possible) Single layer that does it all is ideal Conductive buffer layer Interfacial resistivity <10⁻⁸ Ohm cm² Consider Ni- alloy materials to avoid magnetism, 	Double-sided buffers	

PROCESS SPEED	SURFACE FINISH	Strength	MAGNETISM	New Materials	Optimization	BOTH BUFFERS AND SUBSTRATES (No Category)
				 avoid AC loss Conductivity is high- stability issues Eliminate buffer entirely Single layer or functionally graded buffer layer YBCO on a silver buffer layer Buffer layer has better texture than substrate Simplified architecture in buffer layer 		

TABLE 2.2.2: R&D NEEDED TO ACHIEVE THE BREAKTHROUGHS AND VISION – SUBSTRATES AND BUFFERS

	NEW CONCEPTS	CHEMICAL/PHYSICAL CHARACTERIZATION	MECHANICAL CHARACTERIZATION	UNDERSTANDING OF TEXTURING	Conductive Buffer Layers and Cu Alloy Substrate	Process Control
SUBSTRATES		Develop substrates chemically compatible with YBCO so that buffer layers will not be needed ★★★★	 Predictive modeling of stress-states in the substrate ◆ ◆ ◆ ◆ Mechanical characterization of new substrates ◆ 	 Study and modeling of texture in relationship to microstructure → → → → → TEM studies of initial stages of nucleation and secondary recrystallization (substrate) texture 		
SUBSTRATES AND BUFFERS	 Round wire Identify filamentary crystal substrates Buffer and YBCO or IBAD on round filaments 	Research on diffusion dynamics through buffers and substrates ★★★★★★★		Texture maps (EBSP) that distinguish between in-plane and out-of-plane	 Put more effort into new high conducting alloys and buffer deposition on those alloys → → — Rolling/ texturing of Cu alloys 	 Feedback process control ◆◆◆◆◆◆ R2R XRO (comparable texture) R2R IR (comparable strain) Ellipsometry (thickness) Build prototype control/monito ring systems (portable) and test at different sites Define critical process parameters, how to measure them, and how to maintain system in correct window processing all in situ real time Involve outside

	New Concepts	CHEMICAL/PHYSICAL CHARACTERIZATION	MECHANICAL CHARACTERIZATION	UNDERSTANDING OF TEXTURING	Conductive Buffer Layers and Cu Alloy Substrate	Process Control
						vendors to "adapt" short length processes to long length – XRO, composition, thickness, etc.
Buffers	 Put more effort into solution-based deposition techniques ◆◆ 	 Elucidate how buffer layers influence twin structure development in YBCO ◆◆◆ Doping of buffers to enhance performance Comparative study of candidate buffer layer materials under "standard" conditions to downselect 		 Modeling and experimental study of film deposition and texturing ◆◆◆◆◆ Study initial stages of formation of buffer on substrate (texturing) Study buffer texturing in relation to deposition parameters Nucleation and growth of "thick" solution buffers with uniform coverage ◆◆◆◆◆ Basic understanding of IBAD MgO and effects of all parameters on texturing and processing windows Basic understanding of growth evolution of texture in ISD and IBAD Systematic study of all oxides in relation to ion 	 Conductive buffer with good diffusion barrier and good compatibility with YBCO ◆◆◆◆ Conductive buffers for Cubased tapes – identify Cu and O diffusion barrier materials, compatible with YBCO deposition Identify conducting buffers, study changes in electric conductivity, cation/o diffusion and reactivity with YBCO as function of deposition Doping studies of existing buffers to increase conductivity 	

New Co	ONCEPTS CHEMICAL/PHYSICA CHARACTERIZATIO	UNDERSTANDING OF TEXTURING	CONDUCTIVE BUFFER LAYERS AND CU ALLOY SUBSTRATE	Process Control
		 interaction with their crystal structures (IBAD texture) Systematic study of growth habit of choice Investigate IBAD/ITEX/ ISD texturing mechanisms ◆◆◆ Characterize texture development or loss of texture through thickness of buffer layer 		

TABLE 2.2.3: Key Breakthroughs That Enabled the Vision to be Achieved – Substrates and Buffers

	BETTER UNDERSTANDING (Theoretical Understanding)	Scale-Up to Long Lengths and Widths (~ 100m; several cm)	NEW PROCESSES FOR ENHANCED PERFORMANCE
Substrates	 Basic understanding of texture development and effect of impurities ◆◆◆◆◆◆ Understanding of texturing process in relation to granularity ◆◆◆◆◆◆ Understanding role of impurities and sulfur superstructure in RABiTS starting material ◆ 		 Alternative texturing methods that have following advantages Alternative texturing methods that have following advantages Fast process speed Low demands on substrate Good texture Small grain Good surface finish Simple and high yield Textured Cu-alloy substrates with high electric conductivity and high strength (≥ 300 MPa) (≥ 300
Substrates and Buffers		 Process control and feedback over long times ***** 	 Non vacuum-produced substrate/buffer embodiment Butt-to-butt conductor geometry for current in and heat out YBCO deposition at 600-700°C would enable new buffers/substrates
Buffers	 Understanding improved texture, self-planarization that is achieved with SrRuO3 → may lead to new buffers with even better texture → → → Understand texture mechanisms in buffer that gives better texturing than substrate Buffers with sharper texture than substrate Self-planarizing buffer layers for ISD Understand buffer/coated conductor reactions for specific buffers with specific YBCO processes 	All electrochemical deposition of buffer layer(s)	 Conducting buffers with low interfacial resistivity A A A A A A A A A A A A A A A A A A A

(Comment: to enable critical developments and breakthroughs, a long-range fundamental approach is needed)

TABLE 2.2.4: FIVE MOST WANTED – SUBSTRATES AND BUFFERS

TOP 5 R&D AREAS	KEY TECHNICAL ELEMENTS	ACHIEVEMENT METRIC(S)	YEAR(S) OF Accomplishment (Milestones)	Related Activities – Linkages
Study and modeling of texture in relation to microstructure	 Theory of texture in metals Deformation parameters which control texturing in metals Experimental study of effect of microstructure on texturing 	 Able to predict texturing (misorientation) parameters in substrate Ability to control grain size 	 <5° 2005 <2° 2008 (consistently) 	 Results assist manufacturing of textured metal substrates Couple heavily with texture community
Modeling and experimental investigation of film deposition and texturing	 Establish theory Investigate and improve buffer texturing methods (IBAD, ITEX, ISD,) by experiment, analysis, simulation, and test of models 	Able to predict texturing (misorientation) parameters in buffer	 <5° 2005 <2° 2008 (consistently) 	Results used to improve cost and performance of buffer manufacturing
Conductive buffers with good diffusion barriers and compatibility with YBCO	 This system would be configured as follows: YBCO, oxygen barrier, cation barrier, and then conductive metal tape Oxygen barrier layer must have coexistence of electrical conductivity and low O diffusivity. High thermodynamical stability Cation barrier layer must have coexistence of electrical conductivity and low cation diffusivity Cation barrier layer must have coexistence of electrical conductivity and low cation diffusivity N-type oxides? 	 Identify conducting oxides compatible with YBCO and with low oxygen diffusivity Identify cation barrier material with low Cu diffusivity at high temperatures and high electrical conductivity Optimize: Structure Thickness Deposition parameters Interfacial resistivity Demonstrate a stable conductor with J_E = 30-40 kA/cm² (side benefit of increased stability) 	 Show feasibility by 2005 	 Relates to diffusion dynamics Linked to Cu-alloy tape developments
 Research on diffusion dynamics through buffers and substrate 	 Understand effect of buffer crystalline perfection on diffusion coefficient Study mechanisms of oxygen diffusion through the metal substrate: Does it happen? Is it important Understand bulk vs. grain-boundary diffusion through functional buffer layers 	 Optimize for thinnest and highest- quality architecture (single buffer layer?) 	 Basic understanding by 2005 Optimization by 2007 	Relates to conductive buffer layers

TOP 5 R&D AREAS	KEY TECHNICAL ELEMENTS	ACHIEVEMENT METRIC(S)	YEAR(S) OF Accomplishment (Milestones)	Related Activities – Linkages
Predictive modeling of stress states in all layers	 Define parameters that critically influence stress states of layers of the conductor Need experimental measures of actual stress states (x-ray, other techniques) Need relevant materials properties (thermal expansion, Young's modulus, lattice mismatch, others) Use model to predict effect of various architectures on critical strain of YBCO 	 Good agreement between model and e system, i.e., substrate/single buffer - 20 Build complexity of model to include ac - 2005 Include diffusion characteristics? Expert system 	004	Detailed microstructural characterization and determination of growth modes
Feedback process control	 Thickness (± 10%) Texture (2° FWHM) Composition uniformity (± ?%) Roughness (1nm RMS) Tools RHEED, XRD Ellipsometry Auger Optical (visible, IR, UV) Laser interfermometry 	 In-process capability Feedback/correction H₂O control Rastering Temperature/atmosphere monitoring and control Target, precursor additive (sulfur) 	• 2009	 Linked to YBCO deposition Measurement criteria and metrics linked to modeling results This is used ultimately by manufacturers
Nucleation and growth of "thick" solution buffers with uniform coverage (Note: today, thick (>200 Å) buffers cannot be made without cracking, forcing the use of multiple layers to achieve adequate diffusion barrier, thereby increasing cost)	 Define "thick" Thick enough to prevent diffusion (~0.5 micron) Define fracture toughness required to avoid cracking of buffer during drying Search for additives that increase fracture toughness, reduce shrinkage Develop, characterize solution chemistry that gives uniform coverage Need fracture toughness data on buffer/additive systems during drying stage Early screening step to test many potential materials, narrow down Ultimately move towards single layers 	Achieve needed thickness without cracks	 Identify good elastome, improve it by 2004 Single layer – 2006 	 Diffusion data or sample tests are used to determine desired thickness Look to results of some ongoing university projects

TABLE 2.2.5: SUBSTRATES AND BUFFERS – SUMMARY

Performance Characteristics

- Consistently produce long lengths (>500 m) of complete substrate with buffer layer with good properties
- Simplify architecture by reducing number of layers (to drive cost down)
- To increase J_e, several options should be explored (double-sided buffers, conductive substrates)
- Substrates should be non-magnetic, preferably conductive
- Bottom line: buffers and substrates are capable of sustaining high J_c

Key Breakthroughs

- Basic understanding of texture development and effect of impurities
- Understanding of texturing process in relation to geometry
- Process control and feedback over long times
- Conductive buffers with low interfacial resistivity
- Single solution buffer, double-sided, 500A/cm l_c (to increase width)

R&D Activities

- Research on diffusion dynamics through buffers and substrates
- Predictive modeling of stress states in the substrate
- Study and modeling of texture in relation to microstructure
- Modeling and experimental studies of deposition and texturing
- Nucleation and growth of "thick" solution buffers with uniform coverage
- Conductive buffers with good diffusion barrier and compatibility with YBCO
- Feedback process control

Take-Home Messages

- Lots of work to do!
- Substrates and buffer layers are the platform to HTS coated conductors they are critical pieces of the entire CC.
- Process control to obtain length and width is critical to cost-effective manufacture of substrates and buffers.
- Many of the other priorities described are aimed at improving substrate and buffer performance.
- Considering the vision time frame, working with other communities (e.g., process control industry) to accelerate development and scale up may be mandatory.
- Fundamental research and innovation is still strongly needed.

2.3 Discussion Group 2: RE-I23 Nucleation, Growth, and Flux Pinning

By 2010, a fully mature coated conductor product should have the following characteristics: 100 A, 1 cm width, 1 micron film, at 3T and 77 K. A production plant should be able to produce 120 Km/day of this product.

Critical technical breakthroughs in microstructure control, growth and stability, current sharing architecture and geometry, and scale-up are needed to achieve these targets.

Research priorities to achieve the 2010 vision include:

- Fast characterization methodology and new instrumentation
- Understanding J_c on all relevant length scales

Participants: RE-123 Nucleation, Growth, and Flux Pinning			
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Don Kroeger	ORNL		
Don Leibenberg	ORISE		
David Larbalestier*	University of Wisconsin		
Hee-Gyoun Lee	SuperPower		
Beihai Ma	ANL		
James Voigt	SNL		
* Report Out Presenter			
FACILITATOR: JOSEPH BADIN, ENERGETICS, INCORPORATED			

- J_c as a function of thickness
- Determine microstructure development at all relevant length scales
 - Systematic microstructural studies, TEM, SEM, etc.
- Process understanding through thermodynamic and kinetic modeling of processing including nucleation kinetics of defects.
- Systematic studies on chemical additions, doping and substitutions and their effects on properties
- Phase diagram studies
- Understanding and measuring AC losses
- Develop template films on round wire/texturing round wire.

These R&D activities will guide texture development in materials and methods to control pinning. In order to advance to large scale manufacturing there needs to be expertise in growing good films fast and in modifying materials to maximize J_c and to simplify fabrication. There needs to be fast, real-time characterization methodologies. In addition, novel approaches that are high-risk, high-payoff need to be pursued.

TABLE 2.3.1: 2010 – CRITICAL TECHNICAL DEVELOPMENTS TO ACHIEVE ENVISIONED CONDUCTORS (Needed Breakthroughs)

	Microstructure to produce desired properties	RE-123 growth and stability	Architecture Issues	Scale-up Issues
2005	Intrinsic, extrinsic, or both operating for J _c (d) dependence?? Microstructure control at high growth rates.	RE123: $\Delta T_c = +3$ K; Additive pinning; Growth of RE-123 at lower temperatures (< 700°C)	Development of improved pinning form SC/Cap layers or lattice mismatch; Determine effects of parallel path widths on AC losses	Uniformity of deposition Length, width
2006	Identify pinning defects and determine the elementary pinning force per defect. Elimination of percolation due to grain boundaries.	Understand origin of flux pinning Rapid oxygenation process for all processes.	Development of simplified buffer layer architecture. Current sharing architextures (e.g.) double side tapes, conductive buffers.	Determine limit of growth rate / throughput
2007	Devise processing route to achieve high density of the pinning defects (with no degradation of J _c)	Reproducible control of liquid to maximize growth rate and optimize microstructures	Reduce grain size in RABiTS to < 5µm.	Incorporation of flux pinning technologies
2008				YBCO filamentation – AC losses
2009	A route to achieve alignment of round wires, etc?			High growth rate and throughput
2010			Round wire architecture	Round wire technology.

TABLE 2.3.2: R&D ACTIVITIES TO ACHIEVE 2010 VISION (RAW LIST)

- 1. Systematic studies of chemical addition / substitution for better performance.
- 2. Purity of precursors / starting materials.
- 3. Comprehensive study of cost vs. performance.
- 4. Develop deposition / processing technology for round wire technology
- 5. Fast characterization; methodology and new instruments
- 6. Correlation of length scales with properties (Microstructural vs. mesoscopic)
- 7. Processes for insertion of flux pinning structures
- 8. In-situ characterization for process modeling during growth
- 9. Kinetics of crystallographic defect formation
- 10. Measurement of Jc of individual grain boundaries to determine effects of types of misorientation
- 11. Study mechanisms of defect generation and defect formation and microstructure evolution (TEM and modeling)
- 12. Systematic Microstructural studies TEM, SEM, etc.
- 13. Thermodynamic and kinetic modeling of processing, nucleation and kinetics
- 14. Jc -- thickness (film thickness and through-thickness film Jc)
- 15. RE substitution
- 16. Determine liquid phase field for selected systems
- 17. Study effect of growth rate on Jc / defect formation
- 18. Control studies to introduce specific defect types (effect on $Jc(H, \emptyset, T)$)
- 19. Understand phase stability under relevant processing conditions.
- 20. RE solid solubility as f(P(O2), T)
- 21. Fundamental limits on strength of flux pinning in RE-123
- 22. Develop method to produce and control property flux pinning and rapid oxygenation.
- 23. Develop instrumentation to support on-line Ic measurements.
- 24. Improve modeling of real tape/wire stability/dc/ac losses
- 25. Broaden deposition window T, P(O2)
- 26. Grain boundary understanding at atomic level.
- 27. Develop compositional and processing for small grains in textured metals.
- 28. Measure AC losses in striated YBCO conductors.
- 29. AC losses.

TABLE 2.3.3: R&D ACTIVITIES TO ACHIEVE 2010 VISION (SORTED LIST)

Characterization

- 1. Fast characterization methodology and new instrumentation (6 votes)
- 2. Process control tools (1 votes)
- 3. Develop instrumentation support for on-line Jc measurement (quality control)
- Incorporate characterization for process monitoring during growth XRD, Raman, Auger, etc. (4 votes)

Understand J_c on All Relevant Length Scales

- 1. Measure Jc of grain boundaries to determine effects of types of misorientations. (1 vote)
- 2. Jc as a function of thickness (8 votes)
 - a. Variable thickness of films.
 - b. Through thickness of the film
- 3. Effect of growth rate on Jc / defect formation (4 votes)
- 4. Develop processes to install flux pinning defects (8 votes)
- 5. Control studies to introduce specific defect types; effect of $Jc(H, \emptyset, T)$ (2 votes)
- What are the fundamental limits on strength of flux pinning in RE-123 What is max Jc(B)? (4 votes)

Determine Microstructure Development at All Relevant Length Scales

- Correlation of length scales (defect) with properties mesoscopic and microscopic. (2 votes)
- 2. Build understanding of G.B.'s at atomic level.
- 3. Systematic Microstructural studies TEM, SEM, etc. (7 votes)
- 4. Study of mechanisms of defect formation and microstructure evolution (TEM and modeling)

Process Understanding (modeling)

- 1. Thermodynamic and kinetic modeling of processing including nucleation kinetics of defects, etc. (6 votes)
- 2. Broaden deposition window (T, P(O2),...)
- 3. Determine liquid phase field for selected systems (1 vote)
- 4. Develop method to produce and control –support flux pinning investigations and rapid oxygenation.
- 5. Develop low cost precursors (Ic as a function of materials cost, purity) (2 votes)
- 6. Growth rate experiments characterization (1 vote)
- 7. Cation diffusion issues: time, temperature, barrier layers, etcs. (1 vote)

Chemical Substitutions, Doping, and Other RE Systems

- Systematic studies on chemical additions, doping, and substitutions effects on properties. (4 votes)
- 2. Kinetics of crystallographic RE defect formation
- 3. Understanding phase stability under relevant processing conditions.
- 4. RE solid state solubility as a F(T, P(O2))
- 5. Phase diagram study (4 votes)
 - a. low P(O2) pressure
 - b. role of fluorine
 - c. RE substitution
- 6. RE substitution-effects in presence of liquid phases.

Stability and AC Losses

- 1. Measure AC losses in stirrated YBCO films.
- 2. AC losses (3 votes)
- a. Grain size
- b. YBCO growth in filaments
- c. Current sharing
- d. Tradeoff of modeling twists, filaments, etc.
- 3. Improved modeling of real tape/wire stability/quench/DC AC loss / architecture theoretical modeling needed.
- 4. Develop metal compositions and processing for small grains in textured metals

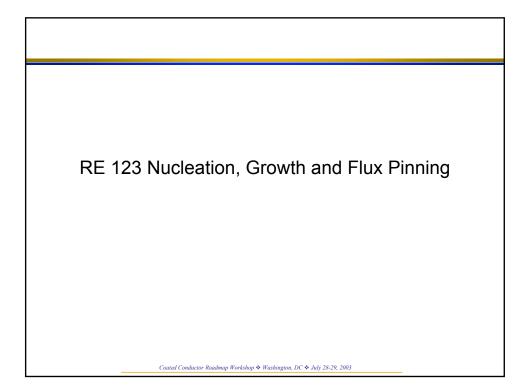
Technical Issues

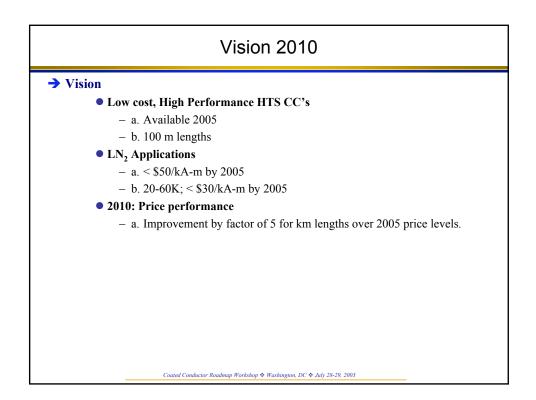
- 1. Develop deposition / processing technology for round wire technology
- 2. Template films on round wire/ texturing round wires (3 votes)
- 3. Characterized ≈ 5cm wide MOCVD / MOD samples vs. processing parameters (1 vote)
- 4. HTS film thickness vs strain tolerance (2 votes)
- 5. Develop process understanding (technical issues)
- 6. Comprehensive study of cost vs. performance

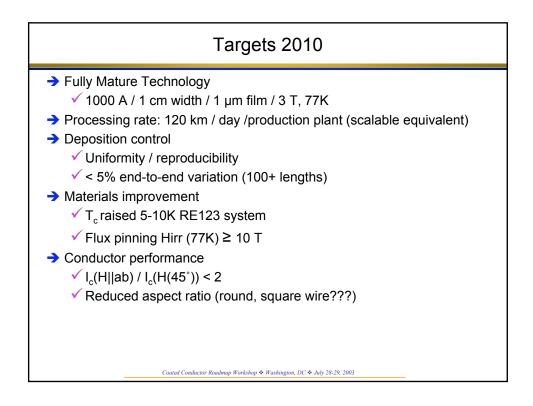
TABLE 2.3.4: TOP 5 HIGHEST RATED R&D ACTIVITIES TO ACHIEVE 2010 VISION.

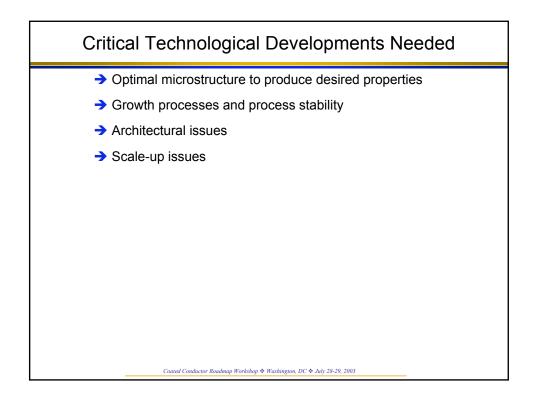
R&D Activity	Technical Elements	Achievement Metric	Year of Accomplishment (2005-2010)	Related Activities / Linkages
Understanding J _c on all relevant length scales	 (1) pinning identify key pin types density, strength, causes (2) Jc vs thickness – identify material dependent contributions to Jc(t) – obtain material independent Jc(t) (3) GB'S understand Jc (Ø,H,T, facet plane) – guide to texture and process development (4) find ways to amerliorate GB effects e.g. doping 	 (1) CC Angular anisotropy better than BSCCO conductors 30 K (2) Understand cross-over from pinning to weak links (3) Understand flaw characteristic determine significance for Jc (4) flat GB Jc dependence out to 10° 77K 	(1) 2005 (2) 2006 (3) 2006 (4) 2007	Guide texture development in materials and buffers. Process understanding to install pins.
Processing Understanding (How to grow films fast)	 (1) Structural and phase characterization (including liquid phases) (2)Increase process rate and related property dependence (3) Liquid phase field for selected systems (4) Thermodynamic and Kinetic modeling (5) Phase diagrams- thermo and kinetic data for modified materials 	Processing method capable of 1000 A/cm-width (2) enhanced flux pinning (3) high rate production	1000 A/cm-width SF (2005) 1000 A/cm-width 3T (2010) flux pinning enhancement (2007) 120 km/day / plant (2008)	Understanding Jc Modified materials Large scale manufacturing
Modify Materials to Maximize J _c , simplify fabrication	 (1) Phase equilibria and stability of RE123 mixed systems (2) Pinning topology – understanding modeling Comparison of 	Higher T _c and J _c 1000 A, 3T, 77K, 1 μm x 1 cm		Process understanding Microstructural studies Jc understanding on all scales

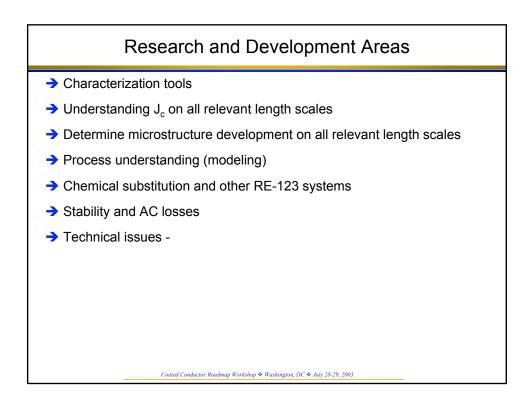
R&D Activity	Technical Elements	Achievement Metric	Year of Accomplishment (2005-2010)	Related Activities / Linkages
	methods (3) Introduction of flux pinning centers – processing, chemical subs, physical subs, porosity, interfacial (4) Comparison of mixed RE- 123 systems.			
Develop fast characterization methodologies	 (1) Defect Correlation database TEM,SEM (2) In-situ diagnostics (RHEED, RAMAN, XRD, lon scattering, AA) (3) Rapid defect detection 	 (1) Database development and dissemination (2) Demonstrated real-time process feedback (3) Demonstrated fast post-mortem defect detection 	2005 - Database started 2005 - real time process via in-situ probe 2007 - demonstration on pilot line 2007 - defect identification over 100m piece length < 5 min	Jc understanding Process development Material modification Large scale manufacturing
Novel Approaches (High risk / high payoff)	 (1) Round wires deposition process Templates and substrates (2) Less anisotropic superconductor 	$J_c > 1 \text{ MA/cm}^2 \text{ at}$ H=0 theshold of interest $\delta < 5$	2005	Substrates Growth mechanisms

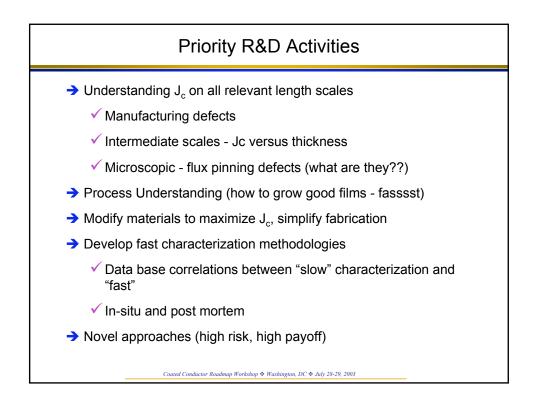












2.4 Discussion Group 3: Conductor Design and Engineering A

Conductor Design & Engineering A

For applications in liquid nitrogen, the wire price should be less than \$50/kA-m in 2007 (not 2005). By 2010, it should be \$10/kA-m. The Vision should be changed to reflect this estimate. The ability to achieve these goals depends on the availability of Title-3 funding and SPI material requirements.

The geometry for conductors must be identified as soon as possible to serve as research targets. The recommended basic building block design for power applications in 2010 is:

- Face-to-face
- Neutral axis
- Alternate conductor designs; Conducting substrate
- ♦ 2-sided coating
- Current carrying capacity of stabilizer

Particpants: Conductor Design & Engineering A			
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John Scudiere*	American Superconductor Corporation		
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Yi-Yuan Xie	SuperPower Incorporated		
* Report Out Presenters			

FACILITATOR: MELISSA EICHNER, ENERGETICS, INCORPORATED

- Low ac loss; geometry; multifilamentary
- Filament size > 10 μm
- Substrate thickness; 25-50 μm
- Multi-layer for ac loss
- Piece length 1000 m
- Physical size < 1 cm for width

In 2010, the recommended performance and operating specifications are:

- ↓ J_E 30-65 K; 3 T; 10,000 20,000 A/cm²
- Stabilizer design
- 200 MPa stress (300 MPa) @ 77 K
- Irreversible strain limit 0.6 % tension; 1% compression (for magnets)
- 2 cm bend diameter
- n value ≥ 14
- 1000 A/cm-width; I_c 77 K; sf
- 100-200 A @ operating conditions
- J_E 10,000 20,000 A/cm² @ operating conditions

In addition in 2010, scale-up and cost-effective manufacturing targets, as well as integration/engineered conductor targets, should be:

- Wide width 10 cm
- ◆ 10,000 km/year and \$10/kA-m
- Minimum 3 U.S. wire manufacturers

- Non-resistant joint (superconducting)
- 100 thermal cycles survivability
- Coils 1000 load cycles

Research priorities to achieve the targets include:

- Develop soldering and connecting technologies to optimize both sides (i.e., no bad side)
- Analysis and modeling of tradeoffs of stability, quench protection, and AC losses for specific applications
- $\bullet~$ Ensure uniformity of 10,000 km, 10cm, and 2 μm
- Process improvements and cost reduction

To achieve the targets by 2010, the process must be identified as soon as possible so demonstrations can start in 2006. The specifications are expected to progress over time and the improvements must be tested to assure that they are meaningful to customers.

TABLE 2.4.1: 2010 CONFIGURATIONDESCRIBE CHARACTERISTICS AND FABRICATION OF THE HTS CONDUCTOR PRODUCT THAT
ACHIEVES THE VISION

	CRITICAL BREAKTHROUGHS REQUIRED (FY04-FY09)	CHARACTERISTICS OF HTS CONDUCTOR IN 2010
BASIC BUILDING BLOCK DESIGN FOR POWER APPLICATIONS (CONDUCTOR GEOMETRY)	 2004 - Coil and wire manufacturers working together 2004 - Test systems for filaments, HTS, multilayer, neutral axis, stabilizer 2004 for 2007 - Pilot facility with new equipment operating 1,000 km 	 Conducting substrate Conducting buffer layer Face to face Neutral axis Low AC loss geometry (multi-filamentary) Substrate 25-50 μ thick Piece length 1000 m Current carrying capacity of stabilizer 2-sided coating Filament size >10 μ Multi-layer for low AC loss Physical size <1 cm for width
PERFORMANCE AND OPERATING SPECS	 2004 (FY05) – 250 A/cm width 20 m 2005 (FY06) – 300 A/cm width 20 m Flux pinning improved 2-3T 2005 - Study and make recommendations for AC loss, quench protection, stability 2006 (FY07) – 350 A/cm width 100 m 2007 (FY08) – 400 A/cm width 1000 m 2007 – Standards upgraded to match real applications I_c definition: 1µ v/cm 2008 (FY09) – 450 A/cm width 1000 m 	 J_e 30-65; 3T 10,000 – 20,000 A/cm² Stabilizer design Irreversible strain limit 0.6% tension 1% compression (magnetic) N value ≥14 100-200 A at operating conditions 200 MPa stress (300 MPa) at 77K 2 cm bend diameter 1000 A/cm width I_c 77K sf J_e 10,000 – 20,000 in operating condition
Scale-Up and Cost- Effective Manufacturing	 2004 – Sliting, lamination demo in – tested 2004 – Demo 4 cm wide manufact (250 A/cm) all steps 2005 – Continuous process to produce 2-sided coating by 2006 – Long length continuous pattering– validate need 2007 – 200-1000 km available for SPI applications 2007 – \$50/kAm 2004 for 2007 – Pilot facility, demo width, handling equipment 2008 – SPI 1000 km 2009 – SPI 2000 km 	 Target Wide width 10 cm 10,000 km \$10/kA-m Min 3 U.S. manufacturers

	CRITICAL BREAKTHROUGHS REQUIRED (FY04-FY09)	CHARACTERISTICS OF HTS CONDUCTOR IN 2010
INTEGRATION ISSUES OF ENGINEERED CONDUCTORS	 2004 – Joining demo (resistant) 2004 – Customers test joints 2004 – Insulation with cryogenics and low partial discharge capability, 60-300K 2005 – Vacuum integrity 2004-2006 – Coil and wire integration (system design) 2004-2006 – Cable and wire integration (system design) 2006 – Insulation vacuum compat. pliable, high break down voltage 60-300k 2007-2008 – Refrigeration available 5 kW at 77K 200-300 W at 35-40K 2008 – Superconducting joint demo 	 Non-resistant joint (superconducting) 100 thermal cycles survivability Coils – 1000 load cycles

MATERIALS	EQUIPMENT AND PROCESSING	CHARACTERIZATION	PERFORMANCE	APPLICATIONS SUPPORT
 Single buffer/simplified buffer (mod – thin – fewer) All MOCVD processing A A A Conducting substrate and buffer A A Conducting substrate and buffer A A Optimize J_c (77K) versus film thickness in long lengths All MOD process (buffers and HTS) A Development of smaller grain size templates (buffer/substrate) ~10µm size Explore "alternate conductor designs" to neutral and face-to-face New IBAD templates (simple conducting) 	 Moving to 10 cm and 25 µm ▲★★★ Tape handling Ensuring continuity In-situ quality control ★★◆ Lower cost manufacturing process development ★♦ Process throughput improvement ♦ Pilot plant equipment and commissioning ♦ HTS dep. rate - increasing 	 AC loss #'s vs. configuration and stability and quench protection (analysis and modeling of tradeoffs of stability, quench protection and ac loss for specific applications) ◆◆◆◆◆◆◆◆ Soldering/connecting no "good side" vs. "bad side" ◆◆◆◆◆◆ Mechanical testing: ∈_{irr} of new geometries/mat. Slitting – fatigue tests joint tensile strength high field electro-mech ◆◆◆ Establishment of accelerated testing of HTS cables 	 Double today's J_c via flux pinning ♦♦♦ Methods of utilizing the angular dependence ♦♦ Uniformity study and optimization across width as well as length for web-coating Testing on wide tape ♦♦ Consistent properties with length ♦ Specify stabilizer current carrying capability based on J_e, practical application: cable, magnet 	 Coil development ◆◆◆◆ Pulse tubes 1 kW @ 77K ◆ Cryogenics, dielectrics and insulation ◆◆ Cable development ◆

TABLE 2.2.4: R&D ACTIVITIES TO ACHIEVE THE VISION

Top 4 Priorities	YEAR OF Accomplishment (2005-2010)	ACHIEVEMENT METRIC (characteristic when successful)	Related Activities/ Linkages	TECHNICAL ELEMENTS (DETAIL)
AC losses values vs. configuration and quench protection – analysis and modeling of tradeoffs of stability, quench protection and AC losses for <i>specific</i> <i>applications</i>	• 2007	 20 kJ magnet successfully and repeatedly quenched Critical path – show stopper 	 2004 – Slitting, grain size, patterned and geometry of conductor Coil development 	 2005 – Test coil AC losses configuration 2004 – Test wire AC losses configuration 2005-2006 – Test stability and quench protection of the coil 2005 – Implement successful AC wire strategy – make narrow tape filamentized, patterned
Process improvement and cost reduction	 On-going – targeted to meeting 2010 goal 	 2010 –\$10/kA-m 2007 – \$50/kA-m 	 Mechanical testing ongoing as new material is developed Ongoing 2010 Improve substrates (non magnetic) – on- going 2005 – Yield, quality control (in situ monitoring) 2006 – I_c testing (non-contact) 2006 – Measurement standards I_c, AC loss Cost analysis – ongoing 	 2006 – Single buffer and simplified buffer (mod, thin, fewer) cost reduction 2006 – All MOCVD processing – cost reduction 2006 – All MOD process I_c improvement in field 2-3T 30-65 K – 2006 – Characterization – 2010 – Implementation 2006 – YBCO J_c improvement with thickness
Soldering/Connecting no "good side" vs. "bad side"	• 2008	 2005 – Effective resistive joint 2008 – Superconducting joint 	 2006 – Conducting buffer and substrate 	 10⁻⁹Ω – cm²
Moving to 10,000 km in 2010, 10 cm and 25 μm – Tape handling – Ensuring continuity	• 2010	Capacity for 10,000 km/yr for SPI and DOD applications	 2007 – Dielectrics 2008 – Refrigeration Ongoing – Cable development 2005 – Textured substrates at full scale production Ongoing – Track international success Ongoing – Validation of cost models Ongoing – ≥3 U.S. manufacturers (wire) 2005-Ongoing – Develop SPI demonstrations and facilitate commercial pull 2005 – Slitting and lamination 2006 – Insulation and joints 	 2004 – Funding in place for pilot 2007 – Pilot facility operation with 1000 km capability per year 1 km piece length Stage gates 2004 – 4 cm process operational 2004 – Demo 10 cm critical path steps 2004 – Companies must select process

TABLE 2.4.3: ANALYSIS OF TOP 4 R&D ACTIVITIES

Conductor Design & Engineering A Vision

- Group recommended to change the Vision from 2005 to 2007 to achieve \$ 50/kA-m
 - Depends on Title-3 funding & SPI material requirements
- By 2010; \$ 10/kA-m; 10,000 km/year

Target (2010)

Critical breakthroughs required

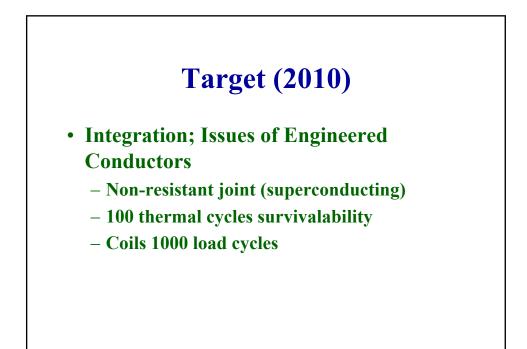
- Basic building block design for power applications conductor geometry
 - Face to face
 - Neutral axis
 - Alternate conductor designs; Conducting substrate
 - 2-sided coating
 - Current carrying capacity of stabilizer
 - Low ac loss; geometry; multi-filamentary
 - Filament size > 10 μm
 - Substrate thickness; 25-50 μm
 - Multi-layer for ac loss
 - Piece length 1000 m
 - Physical size < 1 cm for width

Target (2010)

- Performance & Operating specs
 - J_E 30-65 K; 3 T; 10,000 20,000 A/cm²
 - Stabilizer design
 - 200 MPa stress (300 MPa) @ 77 K
 - Irreversible strain limit 0.6 % tension; 1% compression (for magnets)
 - 2 cm bend diameter
 - n value ≥ 14
 - 1000 A/cm-width; Ic 77 K; sf
 - 100-200 A @ operating conditions
 - J_E 10,000 20,000 A/cm² @ operating conditions

Target (2010)

- Scale-up & Cost-effective manufacturing
 - Wide width 10 cm
 - 10,000 km/year; \$ 10/kA-m
 - Minimum 3 U.S. wire manufacturers





- Materials
- Equipment & Processing
- Characterization
- Performance
- Applications Support

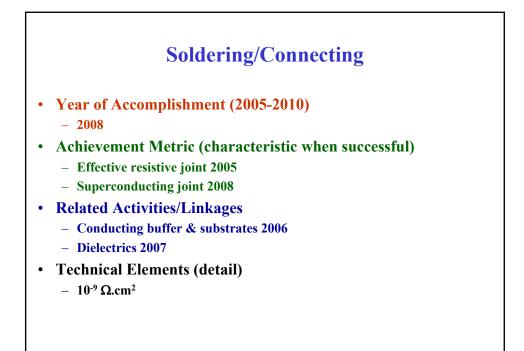


A.C. losses # s-vs. – configuration & quench protection – Analysis & modeling of trade offs of stability, quench protection and AC losses for specific applications

- Year of Accomplishment (2005-2010) - 2007
- Achievement Metric (characteristic when successful)
 - Critical path show stopper
- Related Activities/Linkages
 - Coil development
 - Slitting, grain size patterned & geometry of conductor (2007)
- Technical Elements (detail)
 - Test wire; a.c. losses, configuration (2004)
 - Test coil/a.c. losses configuration (2005)
 - Test stability & quench protection of the coil (2005-2006)
 - Implement successful ac wire strategy in 2005; make narrow tape, filamentized, patterned



Characterization 2006; implementation 2010



Moving to 10,000 km in 2010 Moving to 10 cm and 25 μm – tape handling; ensuring continuity(uniformity) 10,000 km

- Year of Accomplishment (2005-2010)
- 2010
- Achievement Metric (characteristic when successful)
 - Capacity for 10,000 km/year for SPI & DOD applications
- Related Activities/Linkages
 - Refrigeration 2008
 - Tract international success; on-going
 - Develop SPI demonstrations & facilitate commercial pull 2005-on-going
 - Cable development; on-going
 - Validation of cost models; on-going
 - Slitting & lamination 2005
 - Textured substrates at full scale production 2005
 - ≥ 3 U.S. manufacturers (wire); on-going
 - Insulation & joints 2006
- Technical Elements (detail)
 - Stage gates 4 cm process operational in 2004; funding in place for pilot in 2004; demo 10 cm critical path steps 2004; companies must select process in 2004
 - Pilot facility operation w/ 1000 km/year capability by 2007 in 1 km piece length

2.5 Discussion Group 4: Conductor Design and Engineering B

Summary

The design and engineering of the coated conductor will integrate the sub-parts/layers of the conductor into a cost-effective, robust electric transmission device. Critical developments from now to 2010 in the areas of: conductor geometry, performance and operation, and manufacturing will help achieve the vision of the future.

Participants: Conductor Design and Engineering B				
NAME	ORGANIZATION			
Les Fritzmeier*	MetOx			
Don Glenn	BL&A			
Bob Hawsey	Oak Ridge National Laboratory			
Ken Marken	Oxford Instruments			
Venkat Selvamanickan	SuperPower			
Steve Umans	Rockwell/ MIT			
Phil Winkler	Air Products and Chemicals, Inc			
Alan Wolsky	Argonne National Laboratory			
* Report Out Presenter				
FACILITATOR: DAN BREWER, ENERGETICS, INCORPORATED				

By 2010, filaments satisfy the stability criteria to withstand 10 times more fault current than

required by conventional equipment. AC losses, possibly one the biggest challenges for coated conductors, will be 0.25 W/kA-m. In addition to meeting all performance and design targets, coated conductors will be manufactured for less than \$10/kA-m and be capable of 100 meters per hour processing rate.

To reach the 2010 targets, there will need to be critical technical developments in basic building block design, performance, and manufacturing. Practical superconducting joints and field splices will be developed by 2005. By 2007, technical breakthroughs in flux pinning will improve the operation of the coated conductor. AC losses will be low over long conductor lengths in 2007, due to filamentary technical advancements.

Research and development is needed to investigate the basic technology, structure and manufacturing of coated conductors. Activities to characterize the performance and operation are needed, as well as activities to develop tools for modeling and measuring. The top five R&D activities needed to reach the goals and ultimately the vision of 2010 are:

- Understand the process, property and structure of Jc (B, θ , T)
- Develop a method of making and transposing filaments
- Design and test prototype CC's under the device conditions
- Scale-up manufacturing process rates and throughputs
- Understand quench through modeling and measuring the stability and thermal protection

The work breakdown structure of the top five R&D activities can be seen in Table 2.5.4.

It is important to recognize that there is a broad range of activities that need to be completed, in addition to the top five R&D activities, to achieve the coated conductor of the future. Many of these activities are intertwined with each other and the success of one activity can affect the outcome or desired result of another activity (positively or negatively). The impact of these activities will greatly depend on the interaction between the users and manufacturers of coated conductors. It is important that they communicate with each other on the technical specifications and capabilities of the coated conductor product. Finally, a DOE supported and coordinated public/private activity in the design and engineering of coated conductors will provide the resources for organizations to successfully achieve the vision. DOE has unique technical capabilities and experience to facilitate a "Conductor Design and Engineering Initiative" (CDEI).

BUILDING BLOCK DESIGN-	PERFORMANCE AND	SCALE-UP AND COST-EFFECTIVE
CONDUCTOR GEOMETRY	OPERATION	MANUFACTURING
 Filaments with size that satisfies needed stability criteria Quasi-round- able to twist and transpose Splicing technologies for multi-layered, dissimilar electric functions 50 nano-ohms cable Two conducting sides directly connected to superconductor sides 0.4% Critical strain Dielectric coating for all applications Dielectric integration and conductor geometry for high voltage (138 kV) 	 Stability- Withstand 10x fault current for longer than required by conventional equipment Quench robustness and detection Withstand thermal cycles without tape degradation (under pressurize liquid nitrogen) Fatigue requirements 1000 Thermal cycles Critical stress= 300 MPa under operating conditions Science Magnetic Field Applications- persistent current, n>30 that enables NMR insert Power Magnetic Field applications for DC- J_e= 2 x 10[*]8 A/m² at 4 T J_e > 10[*]4 A/cm² at 3T and 65 K 100 A at 4 mm and 1 T AC losses of 0.25 W/kA-m when would in coil or cable (achievement depends on tape and winding) 	 <\$10 / kA-m 100 m/h processing rate 300 A at 4 mm for \$10 /kA-m

TABLE 2.5.1: 2010 TARGETS

BASIC BUILDING BLOCK	PERFORMANCE AND	SCALE-UP AND
DESIGN	OPERATION	COST EFFECTIVE MANUFACTURING
 Superconducting joints and field splices (2005) Complete template (ready for HTS) < 25 microns thick (2005) Dielectric material for cryogenic high voltage applications (2007) 	 Magnet and coil stability and quench protection prototypes (2005) Enough copper for stability, but not too much to decrease J_e (2005) Flux pinning and/or improved J_c (2007) Filamentary conductor that leads to low AC loss and current sharing over long lengths (2007) Develop low aspect ratio for conductor template (2007) 	 Modular design for capital equipment (2005) Slitting technology with <5% reduction in l_c (2005) Uniform l_c over wide substrates (2006) Smaller minimum economic plant size (2007) Reliability demonstrations in devices with second generation (2008)

TABLE 2.5.2: NEEDED BREAKTHROUGHS

STRUCTURE	CHARACTERIZATION	MANUFACTURING	Tools	BASIC TECHNOLOGY
 Develop methods of making and transposing filaments Cut CC into thin filaments Coat with resistive copper jacket Twist into conductor ★★★★ Develop quasi-round textured template Develop process for low aspect ratio conductor (epitaxial J_c required for high value AC) ★ Develop persistent joints Develop copper alloy with single buffer layer and YBCO in 1 km lengths 	 Design tests of prototype CC's Aging Thermal cycling Mechanical environment (handling, winding, etc) ◆◆◆◆◆ Develop measurements of stability and thermal protection ◆◆◆ Characterize mechanical fatigue Explore magneto-optic imaging of AC in CC ◆ 	 Develop process design engineering to scale up processing rates and throughputs Evaluate cost vs. performance trade-offs Quality control A A A Develop splice configuration for Ease of execution Electrical integrity Flexible application (Cable fabrication, machine windings) Effective terminations where current can be injected into all CC layers/filaments Technology for adjoining 2G conductors A Single buffer layer at high rate Slit wide tapes to get uniform l_c in all tapes Repair damage and defects in all process steps Increase deposition rate of HTS layer by 5x 	 Develop device specifications master list (and conductor properties) ◆ Extend statistical modeling from substrate to complete conductor ◆ Develop engineering models Stability Thermal protection Develop quick and effective means of measuring current distribution along width and length 	 Understand process/properties/structure of J_c (B, θ, T) Improve extrinsic pinning to achieve 100 A at 77 K, 1 T in 4 mm widths Enhance Ic by 3-5 x at 50-60 K through materials modification Improve understanding of quench in engineering application that lead to improved conductor design and improve equipment design Improve serious computer modeling of AC current and thermal transients Construct conductor with a variety of copper stabilizers, measure thermal, thickness, and alloys Develop dielectric material for cryogenic high voltage applications "individual tape" Understand substrate issues and limiting texture Improve conductor yield stress and modulus Research current shunting to both sides of the HTS layer Develop higher J_c in films 1-3 microns Identify and eliminate substrate defects

TABLE 2.5.3: R&D ACTIVITIES

TOP R&D ACTIVITY	TECHNICAL ELEMENTS	ACHIEVEMENT METRIC	YEAR OF ACCOMPLISHMENT	RELATED ACTIVITIES/LINKAGES
Develop a method of making and transposing filaments	 Investigate CC geometry in relation to AC losses Subdivide wide filaments Substrates with fine grains Testing filamentary conductor Deposit selectivity on current process Resistive jacket Non-destructive to process 	 25 W/ kA-M at 77 K Develop low AC loss 2G conductor (100-m) suitable for prototype cables and transformers (2007) 	 2010 Testing completed in 2008 	 Modeling AC losses Cryostabilization Pre-commercial lengths (10-100 m) of quasi-round "3G" wire demonstration
Design and test prototype coated conductor's under device conditions- aging, thermal cycles/shocks and mechanical environment (handling, winding)	 Small-scale device Determine critical prototype testing condition for feedback in architecture and design 	 1 m prototype conductor tested Small coil form Repeat if prototypes cannot meet requirements (low AC loss, high field conductor) 	 2005 2008- Develop in-depth understanding of current flow and limitations of basic and advanced conductor geometries 	 Outputs can be used for models Feeds into conductor design Predictive models and properties of 2G components for "expert systems" to produce conductor "building block" designs
Understand process/ property/ structure of J_c (B, θ , T)	 Fundamental characterization and structure properties Testing at different field loading, compare performance of conductors by different HTS process 	 Achieve 100 A at 77 K, 1T in 4 mm widths in minimum I_c orientation J_e> 10⁴ A/cm2 (3T, 65K) 	 2008 2010	 Evaluate alternative RE-123 compositions for optimum J_c (B, θ,T)
Develop process design engineering to scale up processing rates and throughputs	 Understanding upper limits of process (liquid) Increase width of material Understand variability within process area 	 Throughput processing @ 100 m/h linear speed at full width < \$10 kA/m – including stabilization and termination 20 m/h 	201020102005	 Real-time processing monitor and control Single/thin buffer layer (increasing lc at given thickness)
Understand quench in engineering activities	 Measurements of stability and thermal protection Modeling 		• 2005	Develop application modelsFilaments

TABLE 2.5.5 CONDUCTOR DESIGN AND ENGINEERING B – SUMMARY

2010 Targets

- ♦ <\$10 / kA-m
- Throughput processing = 100 m/h
- 0.25 W/ kA-m
- Je > 10⁴ A / cm2 at 3T and 65K

Critical Developments

- 2005- Practical joints and field splices
- 2007- Low AC loss
- 2007- Flux Pinning

R&D Activities

- Understand Process/Property/Structure of Jc (B, θ, T)
- Develop a method of making and transposing filaments
- Design and text prototype CC's under device conditions
- Scale-up processing rates and throughput
- Quench- Measure and model stability and thermal protection

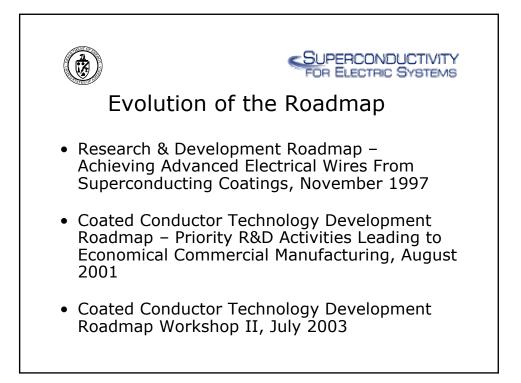
Key Messages

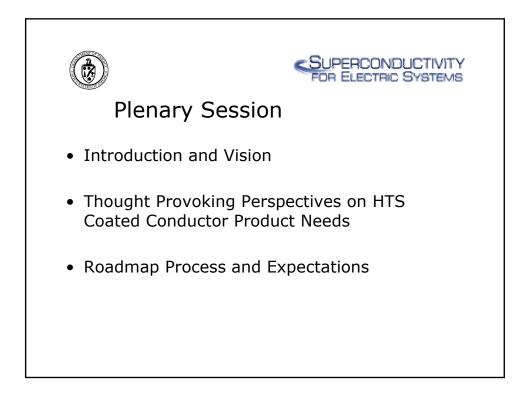
- DOE support coordinated activity- CDEI- Conductor Design and Engineering Initiative
- Interface between users and manufacturers
- Broad spectrum of activity
- AC losses and severe transient in devices

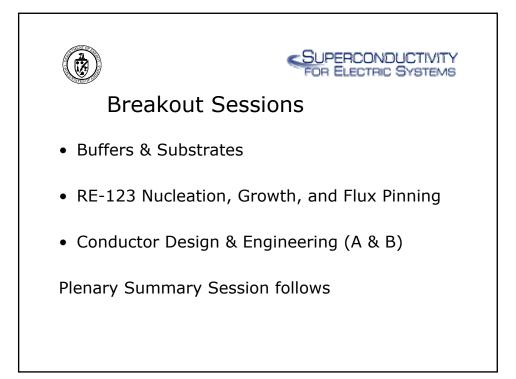
3. PRESENTATIONS

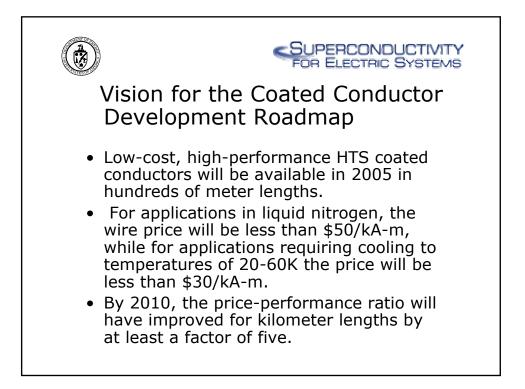
3.1 Introduction and Vision J. Daley U.S. Department of Energy











3.2 Summary MURI Workshop on Fundamental Scientific Issues Underpinning Coated Conductor Development David Larbalestier University of Wisconsin-Madison Summary MURI Workshop on Fundamental Scientific Issues Underpinning Coated Conductor Development

June 11 and 12, 2003 at the University of Wisconsin-Madison organized by David Larbalestier, Malcolm Beasley and Judy Wu from the Wisconsin-Stanford-Kansas-Davis MURI on "Fundamental Scientific Studies of Coated Conductors"



Discussion participants

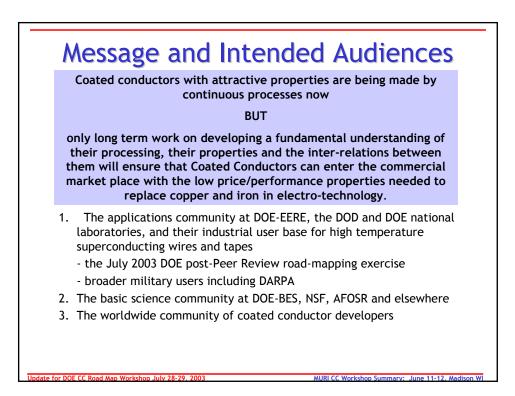
Melinda Adams, University of Wisconsin-Madison Paul Barnes, Air Force Research Laboratory Malcolm Beasley, Stanford University Rabi Bhattacharya, UES, Inc. Ron Bing, Air Force Research Laboratory James Carr

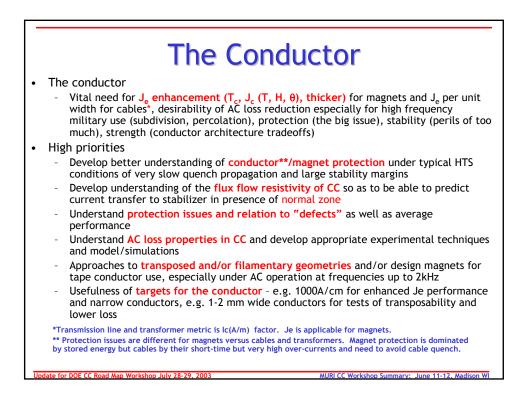
David Christen, Oak Ridge National LaboratoryDean Miller, Argonne National
Charles Oberly, Air Force Rese
Anatolii Polyanskii, University
Jodi Reeves, SuperPower Inc.
Noel Rutter, University of Cam
Daul Grant, Electric Power Research Institute (EPRI)
Alex Gurevich, University of Wisconsin-Madison
Robert Hammond, Stanford University
Timothy Haugan, Air Force Research Laboratory
Eric Hellstrom, University of Wisconsin-Madison
Sang II Kim, University of Wisconsin-Madison
Sang II Kim, University of Wisconsin-Madison
Yuanyuan Lei, Argonne National LaboratoryDean Miller, Argonne National
Charles Oberly, Air Force Rese
Anatolii Polyanskii, University
Jodi Reeves, SuperPower Inc.
Noel Rutter, University of Cam
David Shaw, SUNY-Buffalo
Xueyan Song, University of Wis
Susana Trasobares, Argonne N
Susana Trasobares, Argonne N
Yi-Yuan Xie, SuperPower Inc.

Beihai Ma, Argonne National Laboratory Alexis Malozemoff, American Superconductor Corporation Kenneth Marken, Oxford Instruments Vlad Matias, Los Alamos National Laboratory David Mattox, MicroCoating Technologies Ruling Meng, University of Houston Dean Miller, Argonne National Laboratory Charles Oberly, Air Force Research Laboratory Anatolii Polyanskii, University of Wisconsin-Madison Jodi Reeves, SuperPower Inc. Noel Rutter, University of Cambridge Kamel Salama, University of Houston Justin Schwartz, Florida State University David Shaw, SUNY-Buffalo Xueyan Song, University of Wisconsin-Madison Masaki Suenaga, Brookhaven National Laboratory Mike Sumption, Ohio State University Susana Trasobares, Argonne National Laboratory Judy Wu, University of Kansas Yi-Yuan Xie, SuperPower Inc.

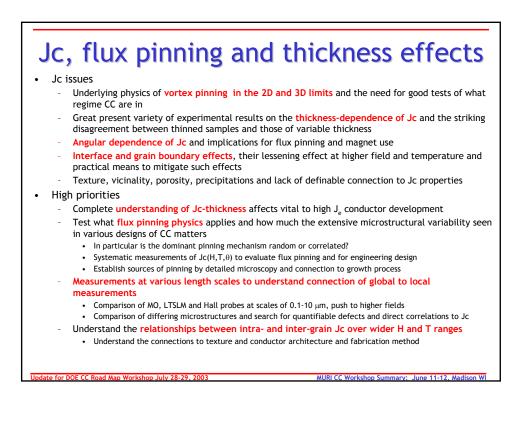
Industry - National Laboratories - Universities - Government

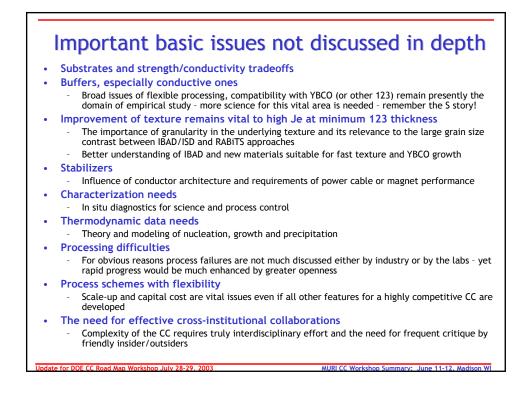
Update for DOE CC Road Map Workshop July 28-29, 2003



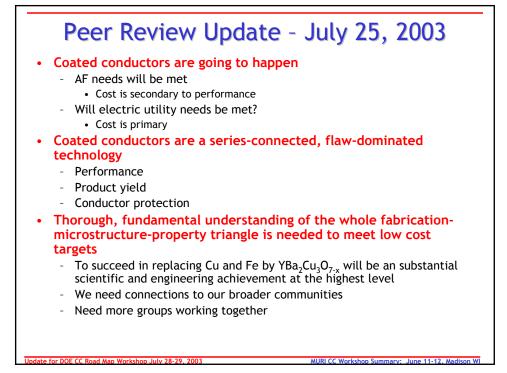


YR	YBCO Growth
-	The vital role of liquid for high growth rates (nucleation and growth), through- thickness microstructure variations, other RE-123 compounds or partial substitution Precipitates, interfaces and grain boundaries
-	Development of microstructure and its significance for Ic and mechanical properties
-	Process control tools
Hig	h priorities
-	 Understand phase stability under process conditions relevant both for high vacuum and "chemical, higher-pressure" routes Understand role of liquid in controlling desired properties Understand reactions with seeds and buffers and their consequences
-	Systematic microstructural studies by SEM and TEM for relevant length scales and properties
	 Understand microstructure evolution and connect to Jc (distinguish flux pinning and connectivity effects)
-	 Build understanding of GBs and interfaces at atomic level Connect theory and experiment at needed levels of complexity and use to ameliorate properties by doping or chemical substitution
-	Explore the higher-Tc 123 systems, e.g. Nd-123 Understand added temperature and field margins
_	Develop the detailed scientific understanding needed for CC processing

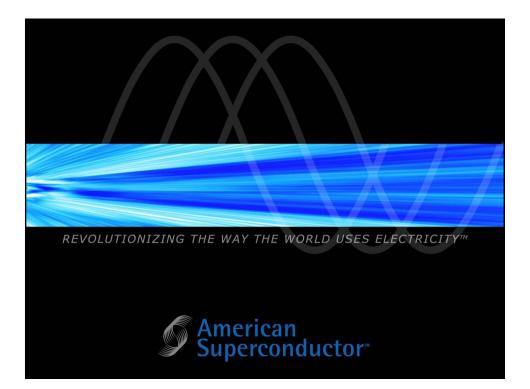


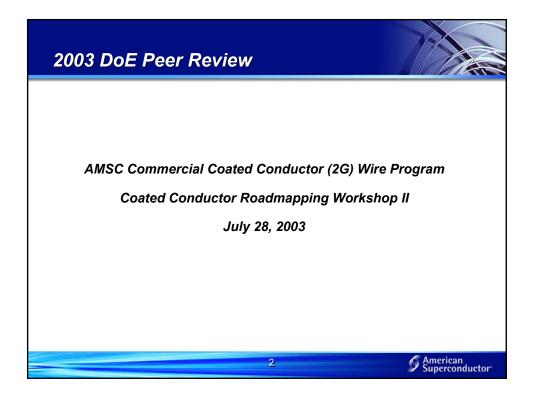


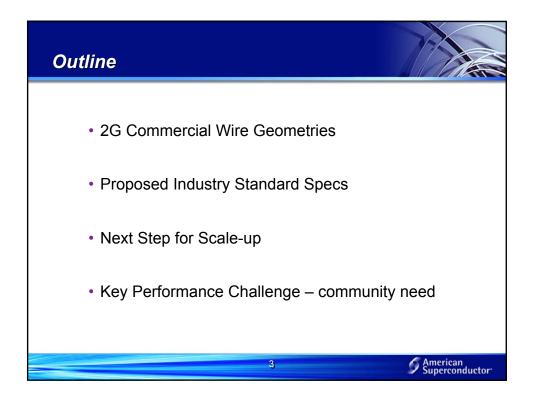


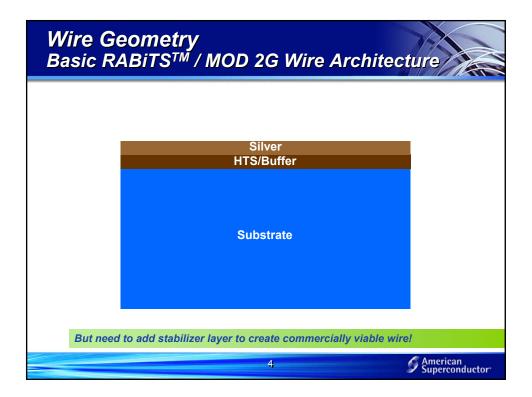


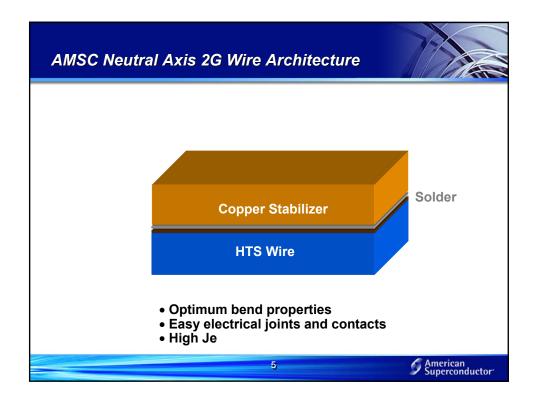
3.3 Revolutionizing the Way the World Uses Electricity John Scudiere American Superconductor Corporation

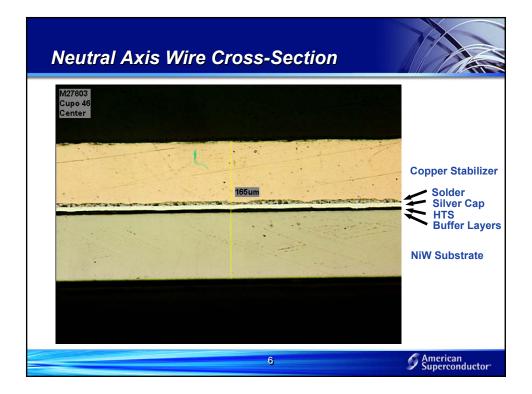


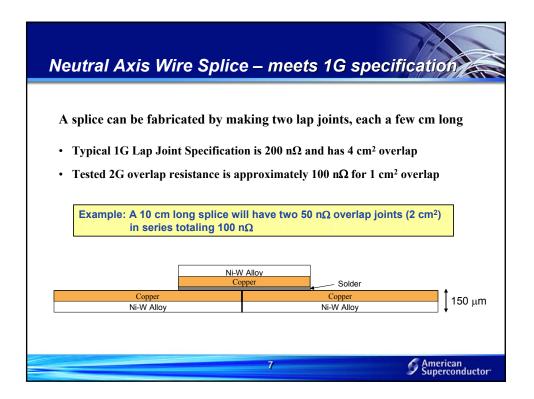


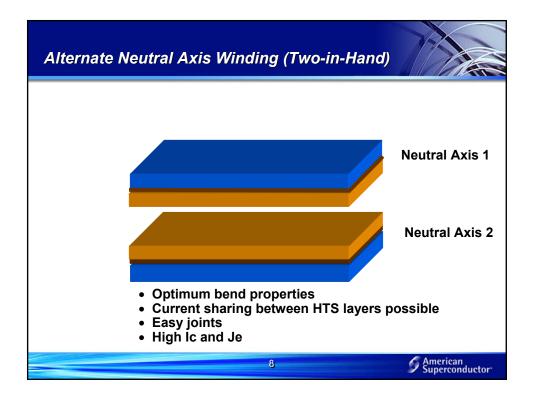


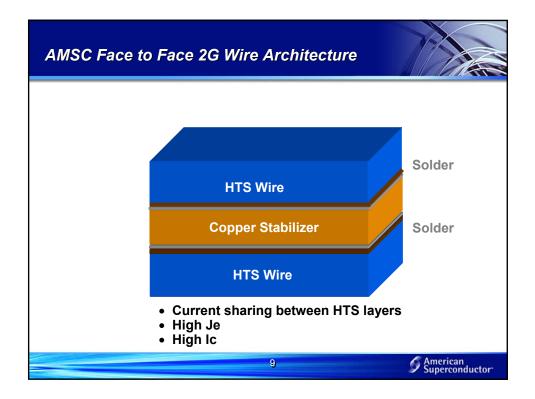


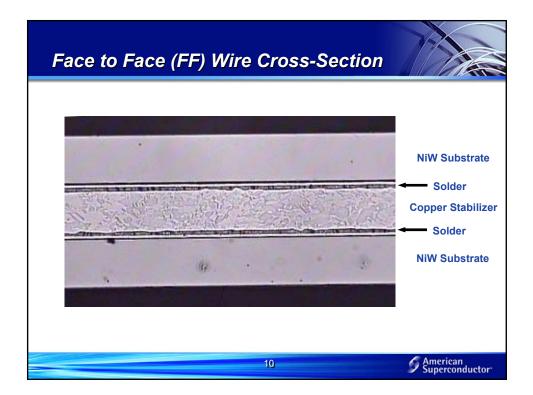


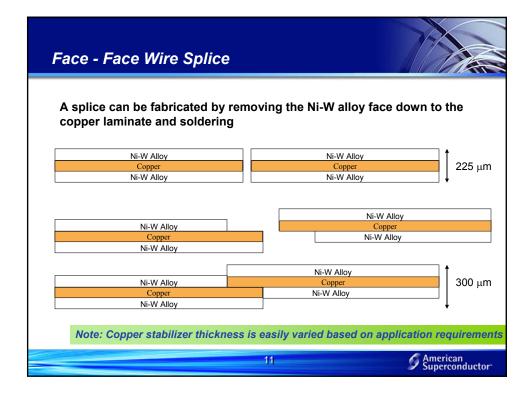






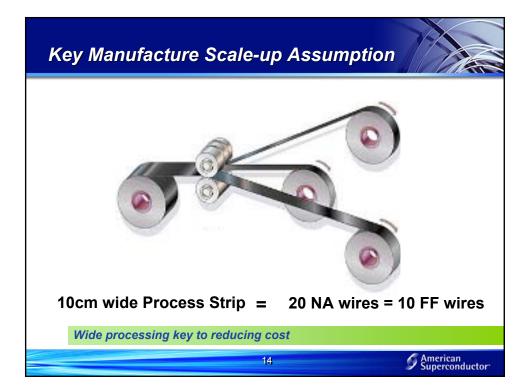


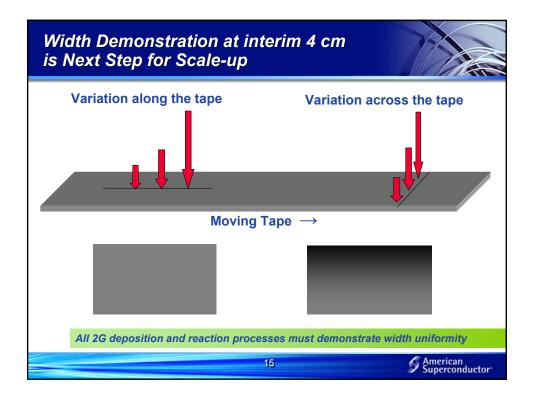


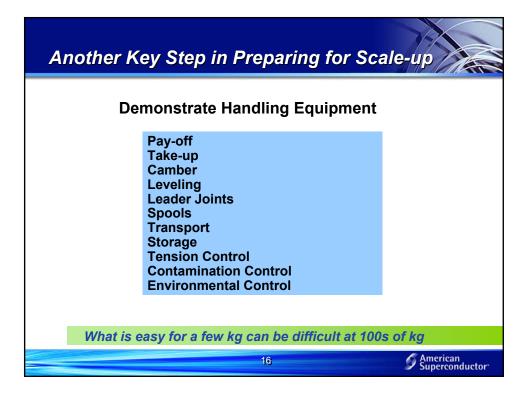


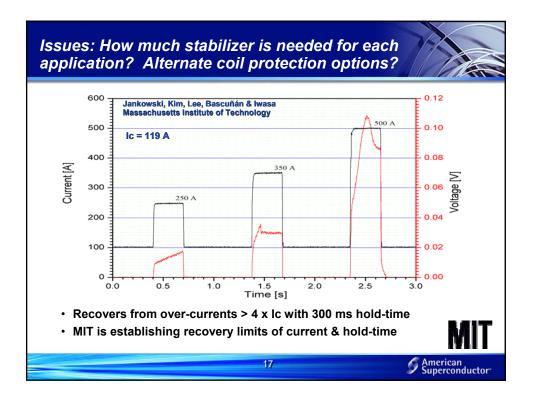
Goomotru	Face-to-face	Neutral Axis
Geometry: Ave. width:	4.1mm	4.1mm
Ave thickness:	0.30mm	0.15mm
Min Ic (77K, sf):	240A	120A
Min Je (77K, sf):	20,000 A/cm ²	20,000 A/cm ²
Critical stress long (RT):	150 MPa	150 MPa
Critical stress c-axis (RT):	20 MPa	20 MPa
Critical tensile strain (77K):	0.4% (cyclic 0.3%)	0.4% (cyclic 0.3%
Critical compressive strain (77K):	0.3% (cyclic 0.2%)	0.3% (cyclic 0.2%
N-value:	14	14
Min Bend Diameter:	70mm	35mm
Laminate Material:	Copper	Copper
Piece Length:	100 - 1000m	100 - 1000m
Price (large volume):	≤\$6/m	≤\$3/m

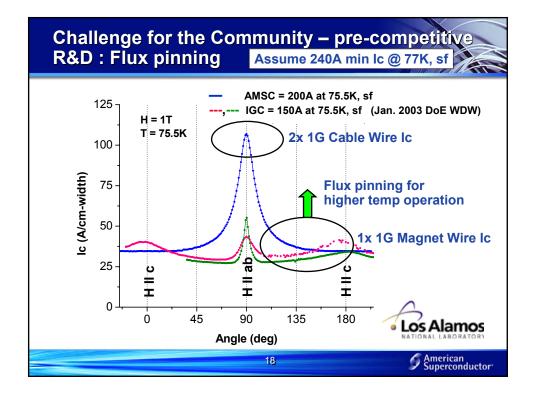


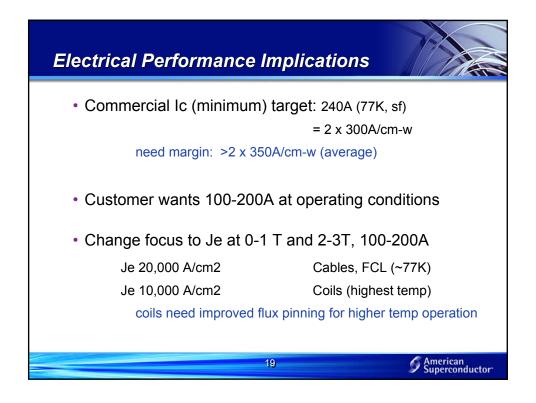


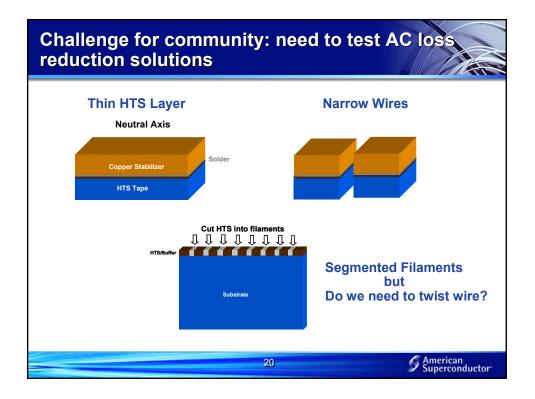


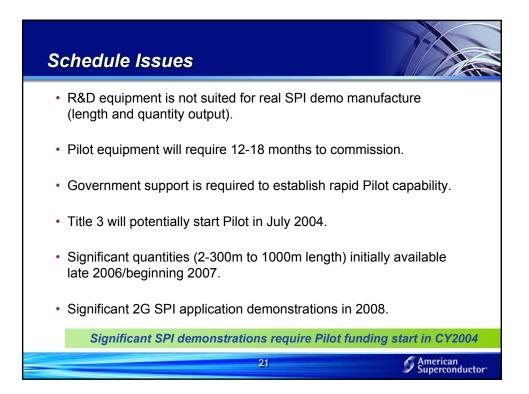


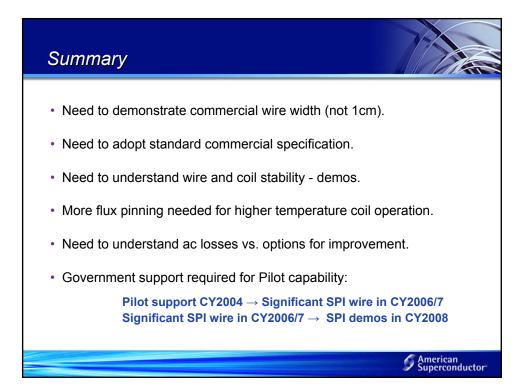


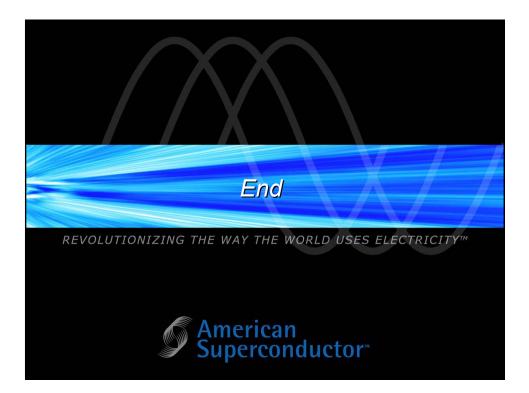


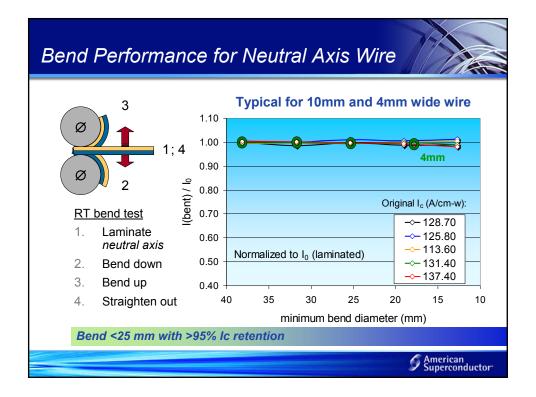


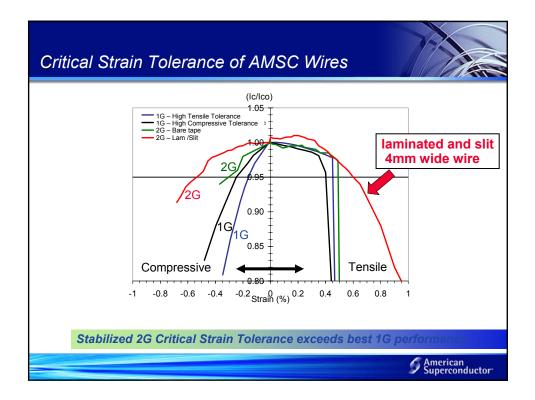


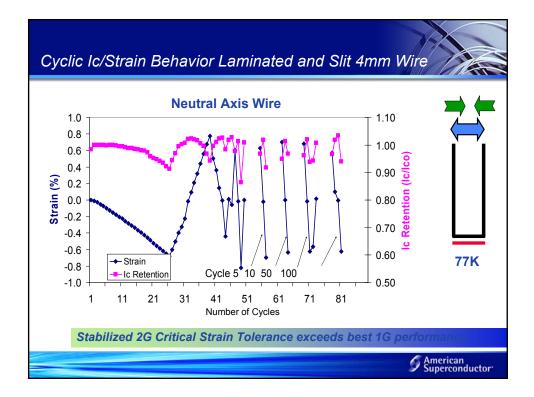


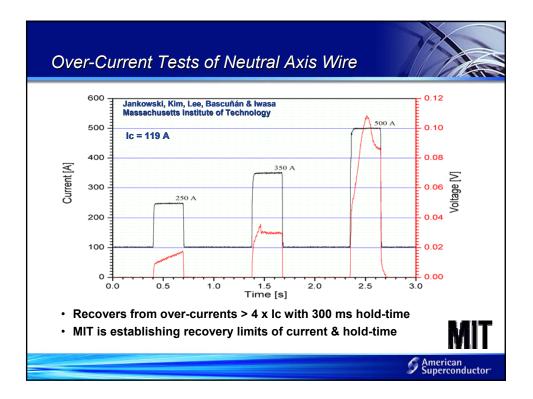


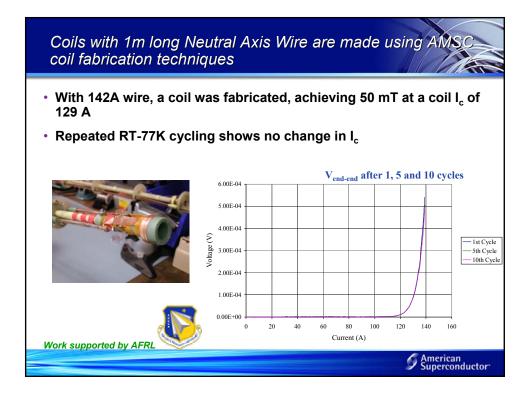


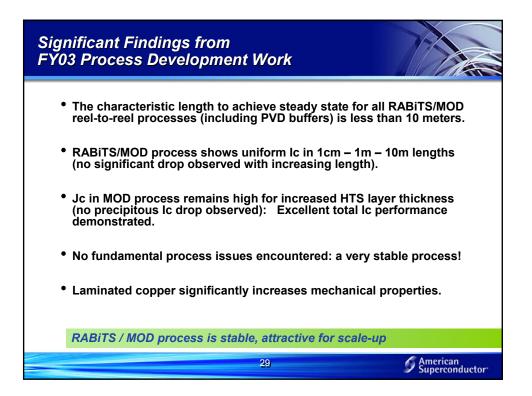




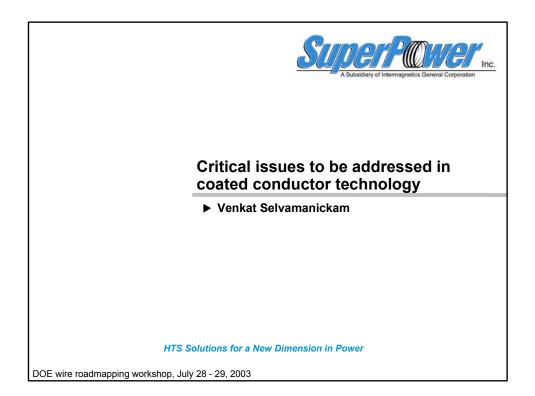


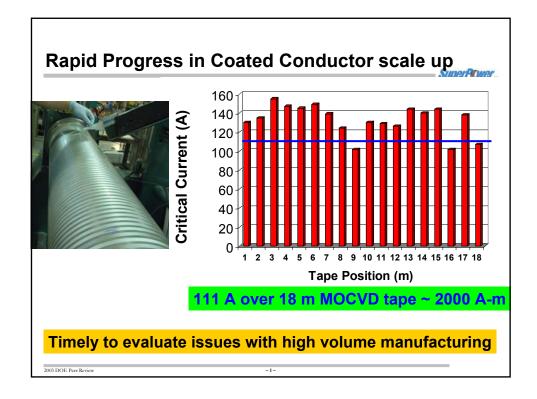


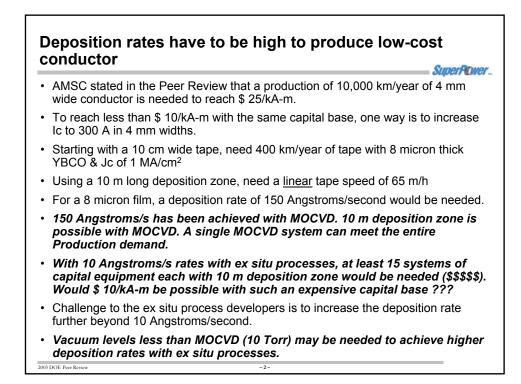


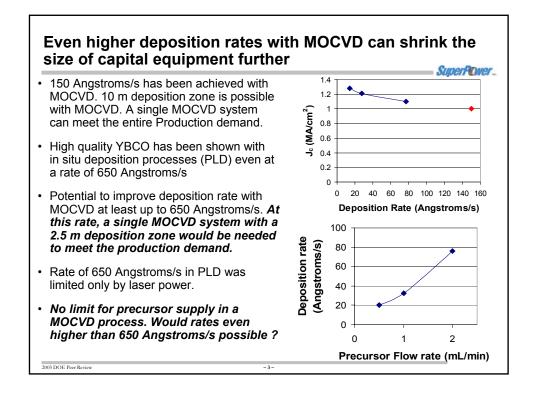


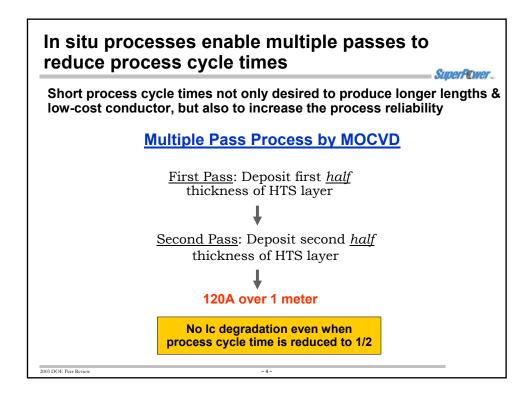
3.4 Critical Issues to Be Addressed in Coated Conductor Technology Venkat Selvamanickman SuperPower, Incorproated

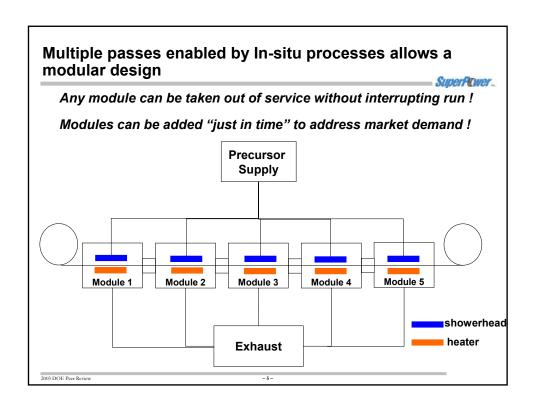


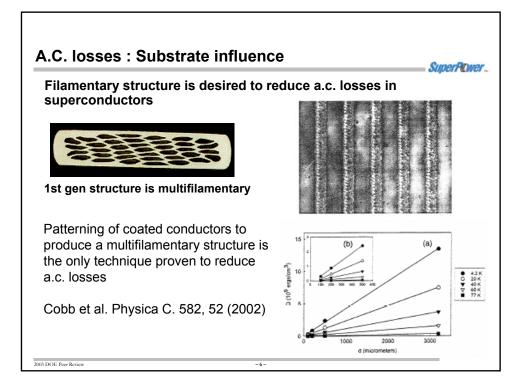


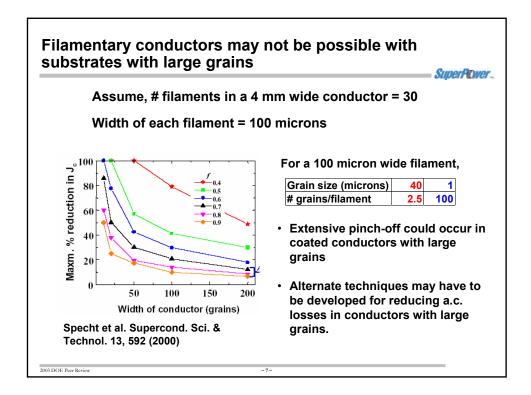


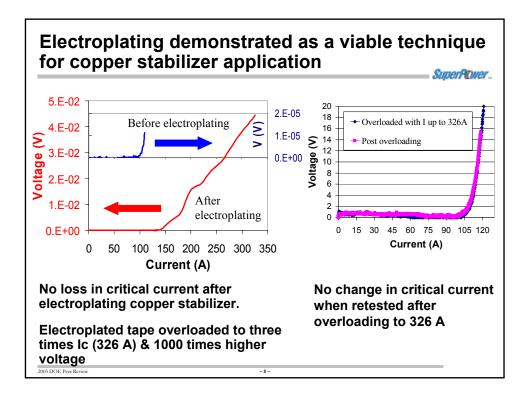


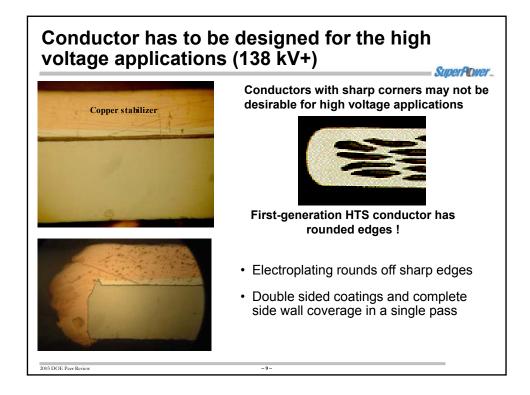


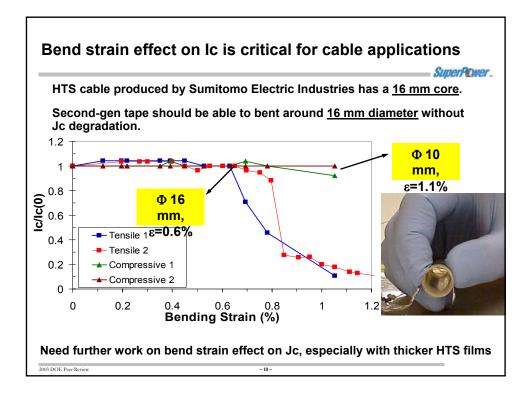


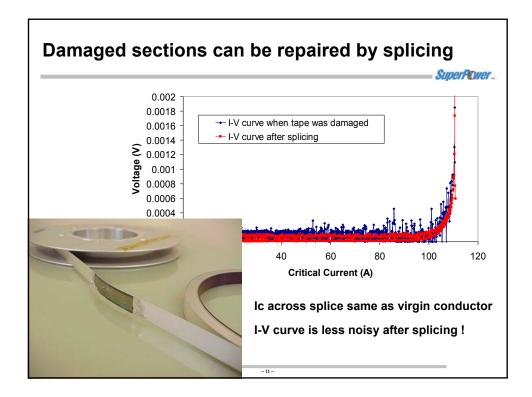


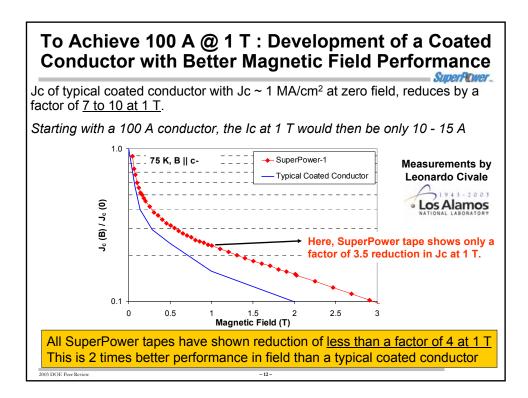


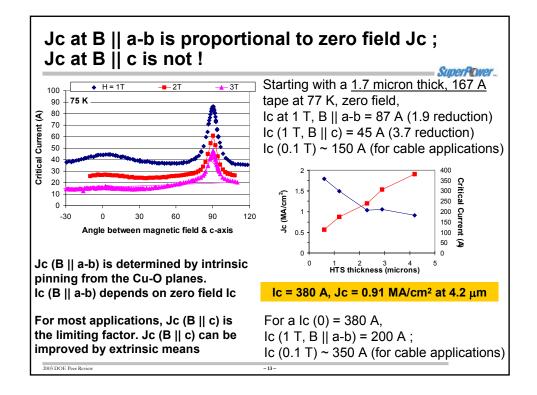


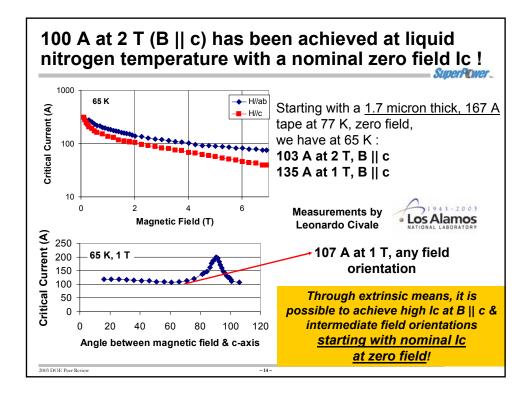


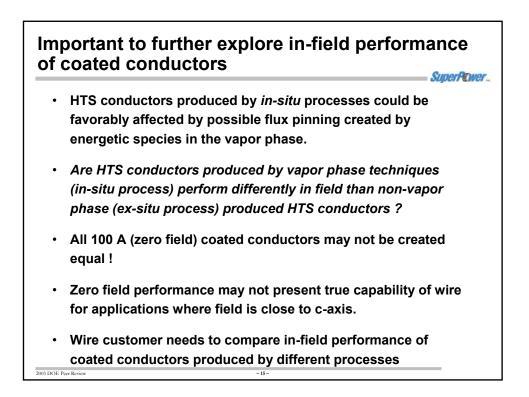


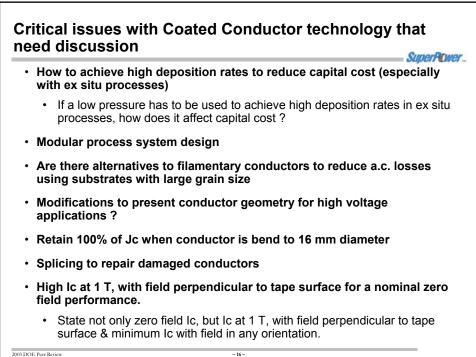






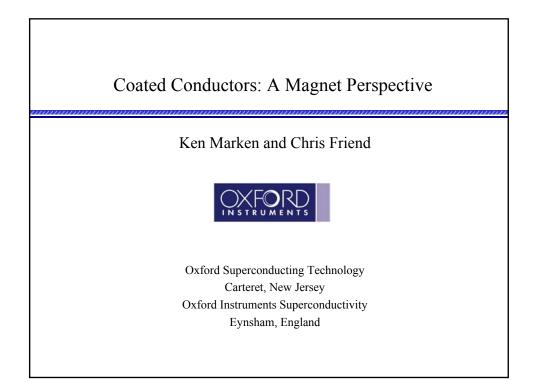


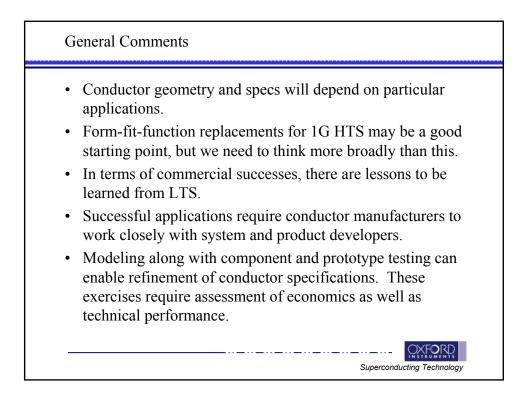


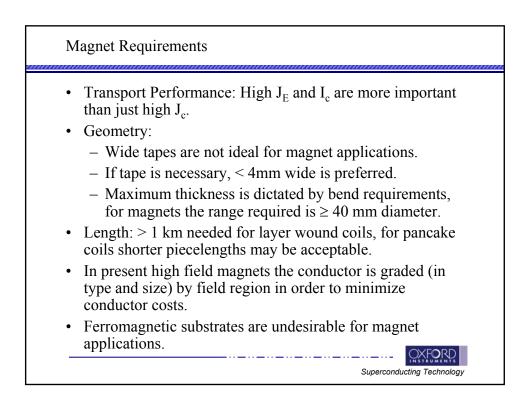


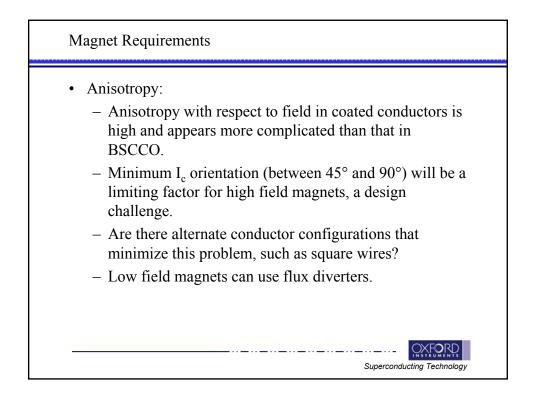
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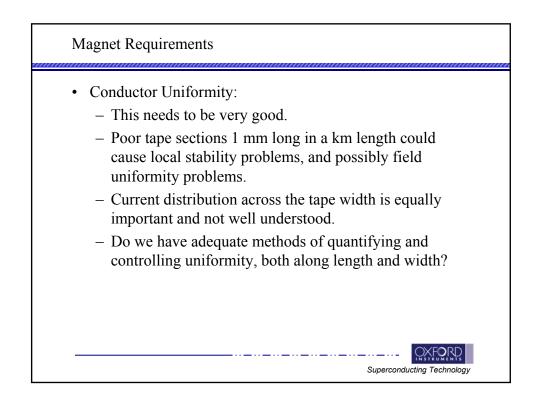
3.5 Coated Conductors: A Magnet Perspective Ken Marken Oxford Instruments Superconducting Technology

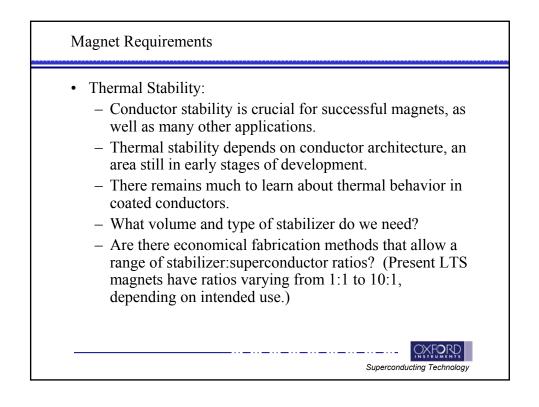


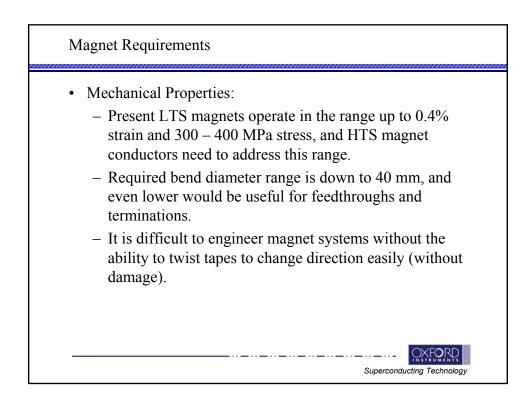


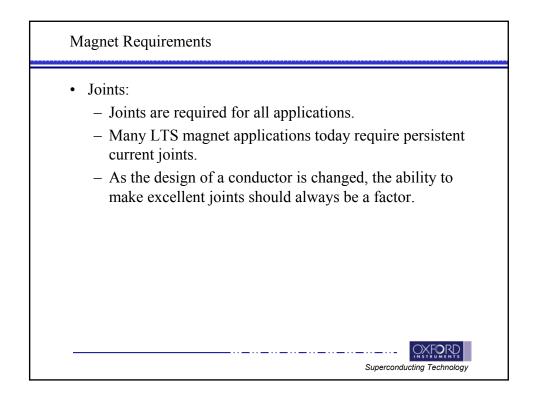


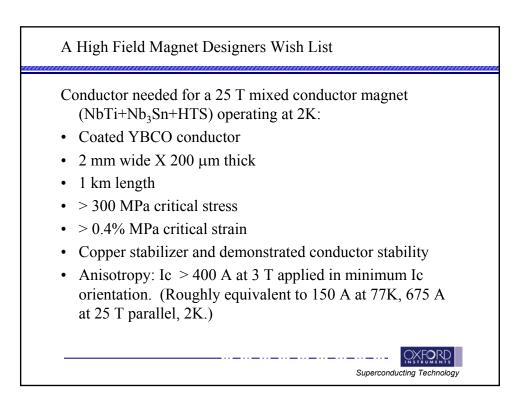




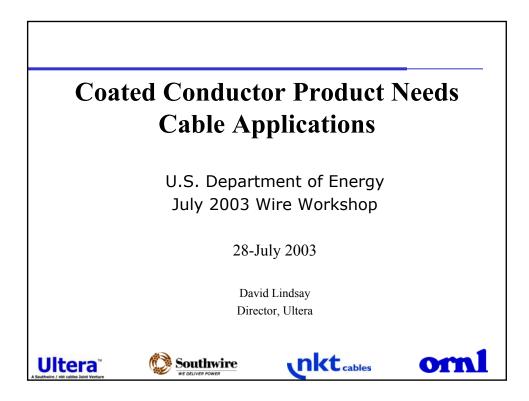


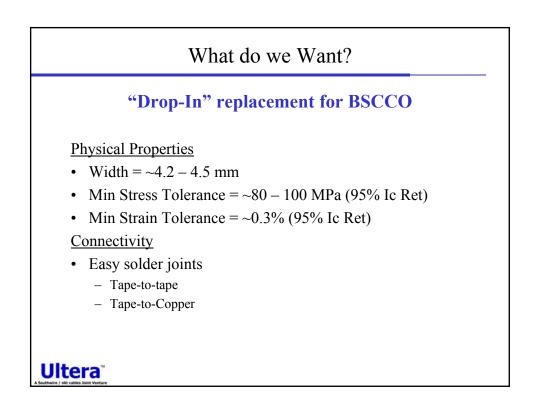


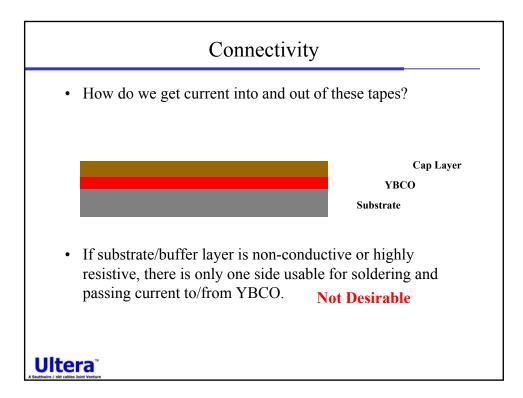


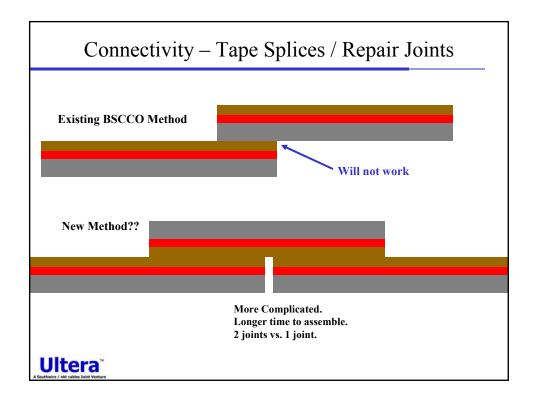


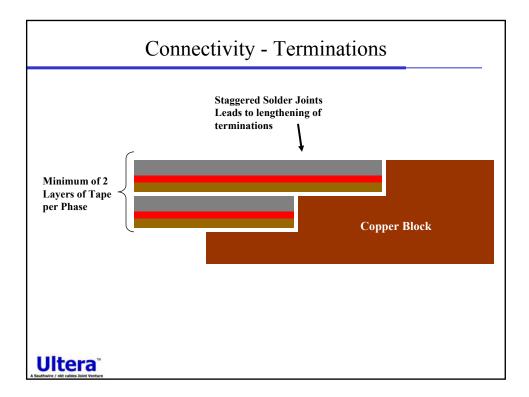
3.6 Coated Conductor Product Needs Cable Applications David Lindsay Ultera

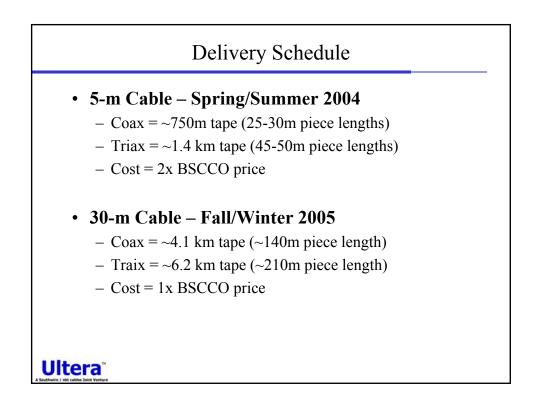


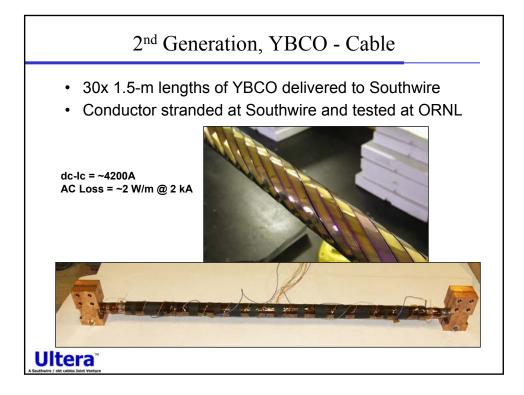


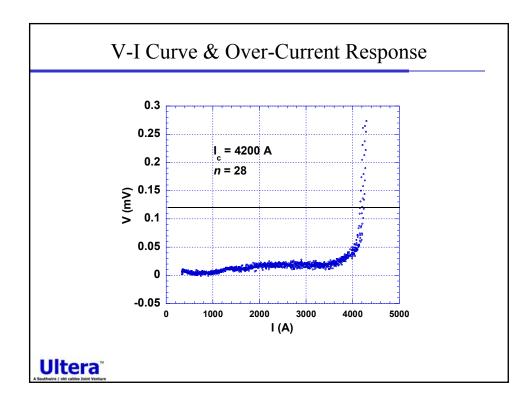








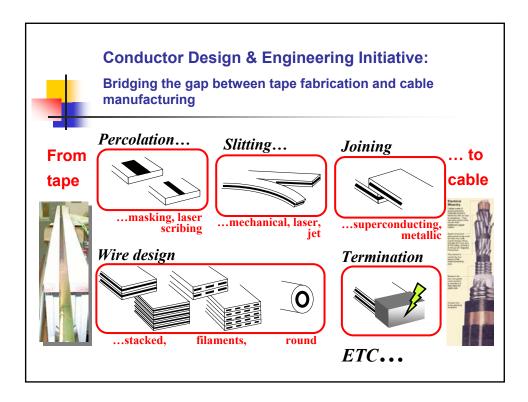


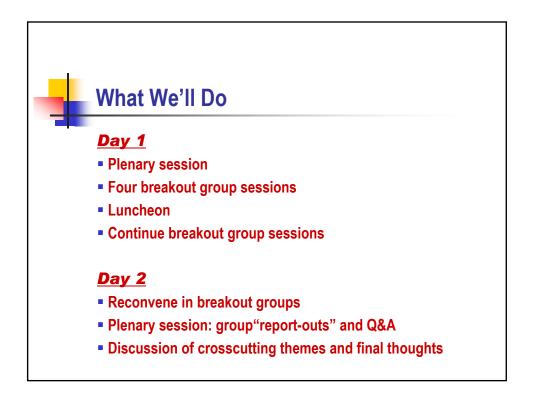


3.7 Facilitated Gameplan Coated Conductor Technology Development Roadmap *Joseph Badin Energetics, Incorporated*

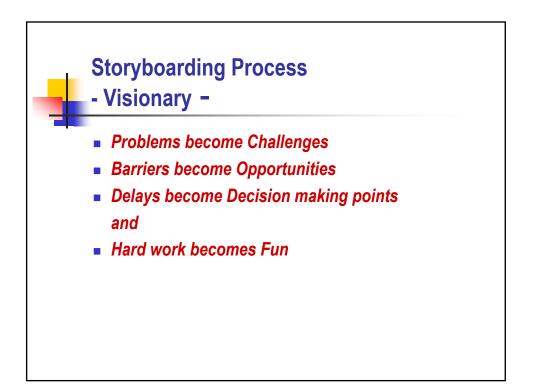


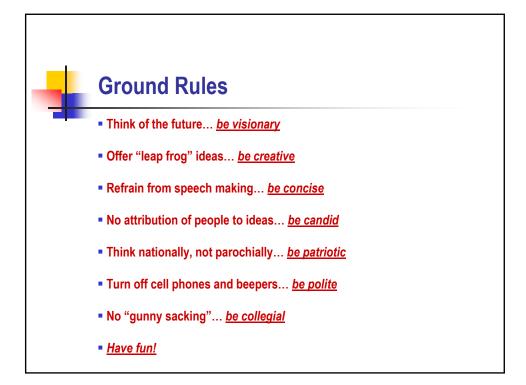












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APPENDIX: YBCO COATED CONDUCTOR ISSUES

YBCO COATED CONDUCTOR ISSUES

The development of coated conductors has reached a critical juncture, whereby on the one hand, the first coated conductor tapes beyond a 10-m length are being produced, while on the other hand, the field continues to broaden in terms of materials and techniques being developed. The workshop aims to assess long-term and short-term goals and needs, starting from an evaluation of the current status for each of the components of a typical YBCO coated conductor, i.e. the metallic substrate, buffer layers, and the YBCO coatings. In addition, we will also focus on the issues towards application and characterization of coated conductors. The speakers are asked to address a number of issues formulated by the organizers and provide their views in their presentation. Each presentation is limited to 10 min. There will be no question period after the presentations, however, at the end of each session, the issues will be discussed as a whole in the context of the multiple views presented.

The following contains a listing of the questions/issues to be addressed for each session. The presenter is asked to comment only on the issues particular to his/her topic and the associated session. Issues not included in the list but considered equally or more important also may be discussed.

Issues related to YBCO film growth:

Current Status

What is the best performance (I_c /cm-width) that can <u>presently</u> be achieved with your process on coated conductor substrates? What is the YBCO thickness, I_c (A/cm-width), J_c ?

What is the performance using currently preferred processing parameters for long length production, taking into account production rate, reliability, etc.? In other words, what is the best compromise now for making a long tape (> 100 m) with reasonably high I_c? What is the YBCO thickness, I_c (A/cm-width), J_c, production rate for this compromise condition?

• Scale-up: next level

What is the maximum length (area) that can presently be produced in a <u>single</u> <u>run</u> (before regeneration of equipment/sources is required)? How can process <u>continuity</u> be maintained beyond regeneration limits?

What is the most sensible, near-term scaling-up step towards: a) higher I_c/cm-width, and b) higher production rate? What obstacles need to be overcome to bring the process to this near-term, higher level?

• Scale-up: long term

What are the advantages of your technique for the fabrication of long-length YBCO coated conductors? Assess which advantages are unique.

What are key issues for large-scale production? Describe pathways for future development. Indicate research and technological needs. Describe a level of development at which your technique may be available for prototype demonstrations requiring: a) > 100 m of tape, b) > 10 km of tape ($I_c > 150$ A at 77 K).

Issues related to Substrate/buffers (IBAD, ISD, RABiTS, ITEX):

• What is the current status of your substrates?

The typical texture that can be readily obtained in short samples The typical texture and uniformity that can be readily obtained in longer samples (up to a meter)

Typical texture and uniformity that can be readily obtained in longer samples (10-100m)

Typical texture obtained in wide samples (at least several cms to several inches)

• What are your process characteristics? Speed of the process

What is limiting the degree of biaxial texture? How can it be improved?

• What are the intrinsic issues?

Surface finish requirements (cleaning, polishing, etc.) and how they are being met?

Effect of surface finish intrinsic to texture development? Or merely to growing thick epi YBCO films?

Strength and magnetism of substrate issues

Mechanical properties of substrate

• What are the future prospects (in the next one year)?

What would be most difficult aspect of the process to scale up to long lengths of 100m?

What would be most difficult aspect of the process to scale up to wide lengths of several inches?

What research areas do you think need focus in order to make this substrate technology viable?

Issues related to New Buffer Layer Technology:

- What is different about your process with respect to other standard Physical Vapor Deposition (PVD) techniques?
- What is the economics of your process? This includes speed, simplicity, minimum buffer layer thickness, processing issues, deposition rates, etc.
- What is the current status of the performance of your buffers? What YBCO deposition technique was used? How long, how wide, how fast, and how good can you make?
- What are the near-term problems that need to be resolved? This includes starting chemicals, furnace designs, process conditions, reproducibility, interaction of buffers with YBCO, substrate surface conditioning, stress related issues, etc.

Issues for applications of Coated Conductors:

- Why would coated conductor be preferred for this application?
- What is your operating field, temperature?
- Desired conductor cost at that field, temperature: from 2005 2010
- Preferred amperage of conductor (is there a maximum?): from 2005 2010
- Preferred conductor width and thickness (including parallel shunt if needed)
- Single piece lengths required
- Properties that include all of these, but not limited to n value at operating conditions Engineering J_c including parallel shunt Bend strain for 10% reduction in J_c Tensile strength at 10% reduction in J_c a.c. losses at operating conditions Joint resistance Uniformity in J_c Magnetic properties (esp. in consideration of substrate)

Issues related to the characterization of coated conductors:

- Describe microstructural issues of YBCO coated conductors that are most urgent for future progress.
- Reel-to-reel transport property measurements. What are the issues and how can they be addressed?
- Discuss quenching and thermal stability studies related to YBCO coated conductors.
- AC losses. What the tape geometry and ac loss measurement issues? Design aspects, ellipse model or strip model, etc.
- What are the advantages and disadvantages of coated conductors compared to BSCCO and MgB₂ conductors?
- Effect of defect distribution on I_c incorporating all the theoretical aspects. What are the most important aspects of both primary and secondary levels of defects? Effect of grain size, pinning centers, etc.
- What are the in-situ diagnostics that need to be looked into for RABiTS, IBAD, etc? Also include YBCO ex-situ & in-situ processes.

Session: YBCO by Pulsed Laser Deposition

- Herbert C. Freyhardt (Univ. of Goettingen) High Rate PLD + IBAD-YSZ
 10 meter, > 200 A/cm, >2 MA/cm², 65-70 nm/min, 1.3 m/h @ 4 mm width FCL: 2500 - 5000 A max 55 f-500L tube YBCO PLD=High Reproducibility
- 2. Yasuhiro Iijima (Fujikura Ltd.) PLD + IBAD-Gd2Zr2O7 30 meter, ~ 1 MA/cm2, 40 A, 0.5 m/h
 - needs improvement on
 - Temperature control, F₂ gas recharge, target degradation,
 - YBCO collection yield (few % to 30-50 %...)
 - ® W-laser, target automatic changer, ...
- 3. Kazuya Ohmatsu (Sumitomo Ltd.) PLD HoBCO + ISD-YSZ, CeO2

High Power Large PLD system; 200 W laser, 250 **f**-target 10 meter, 0.2 MA/cm², 5 m/h 50 meter, CeO₂ buffered Ni metallic tape To achieve 50 meter HoBCO tape within the end of 2002

- 4. Dean Peterson (Los Alamos National Laboratory) PLD + IBAD MgO Multi-layer structure SmBCO/YBCO Thicker and High Ic Conductor 1 meter, > 200 A/cm on IBAD-YSZ 600 A/cm short sample
- 5. Hans Christen (Oak Ridge National Laboratory) Cost of laser
 ® \$33/kA-m at demonstrated values (LANL, Goettingen, Fujikura, 2001)
 ® \$12/kA-m by increase in laser device ability such as collection efficiency
 ® \$3.5/kA-m by Jc increase to 2.5 MA/cm2 and laster tube price 50% down

Cost standard \$ 50/kA-m

Verebelyi (AMSC)	TFA	118A/cm		1m		thick YBCO better texture		High Yield, No high vac svstem	performance & cost over BSCCO	
Izumi (ISTEC)	TFA	153A/cm-w 1µm		10cm	LowTemp.:? LowTemp.:?	Density & Thicker Film	Shorter Low Temp Anneal	Multi: Coating, High Yield, No New Solution: high vac Shorter Time? system	Comparison in Batch & RTR	300A/cm-w, 500m,5m/h
Yoshizumi (MIT)	TFA	96A/cm-w 0.8μm	Low?High(PH 20)	0.6cm				High Growth Rate & Texturing	Flat and Uniform Precursor	
Feenstra (ORNL)	BaF2	270A/cm-w 3μm		бш			Batch & Large Area		Comp. Control	100m/h 4mm- w 5μm YBCO
Suenaga (BHNL)	BaF2	200A/cm-w 5µm/on YSZ- Ni				Batch				1000A/cm-w
O'Neil(3M)	BaF2	45A(2m)		15m		Thick Film High quality conversion	Conversion Rate Evap. Rate	Dense Precursor RTR	Uniformity Conversion rate	
Lee(ORNL)	BaF2	90A/cm-w 0.82µm		1m		High PH20		Low Pressure	Homogeneous YBCO , HF Handling	100m/h 5-10m 200A
Presenter	Procesas	Ic*A/cm-w & Thickness	Compromise Conditions for Long Tanes	Max. Length	Continuity	H	Obstacles Production Rate	Advantages of Your Tech. for Long Tapes	Key Issues (Pathway)	Prototype
		Current	Status		Scale up	Level			Scale up Long Term	

•			•			
Speakers	Shiohara	Strikoviski	Hammond	Lee	Kashima	Donet
Process	LPE	PED	in-situ e-beam evap	MOCVD	MOCVD	MOCVD
Buffer	SOE	Rabits	LaO	IBAD	untextured Ag/ {110}<110>textured Ag	SOE
Best Ic	> 100 A/cm	34 A/cm	150 A/cm	150 A	3.2 A on textured Ag	
YBCO thickness	1 micron	0.4 micron	0.7 - 1 micron	1.2 micron		
Best Jc	1 MA/cm2	0.85 MA/cm2	2.5 MA/cm2	1.3 MA/cm2	0.55 MA/cm2 on textured Ag	0.86 MA/cm2
Long length best performance				90 A over 1 m	2.5 A ; 61,000 A/cm2 over 100m on untextured Ag	
Maximum length before regeneration of sources	Lifetime of crucibles	lifetime of electron sources	rod feed sources in scale up mode (can produce kilometers)	Unlimited ; precursors outside deposition chamber ; no regeneration limits for sources		
Scale up for higher Ic	high crystallinity ; Long oxygen anneal	better understanding of PED process	higher rates (350 Angstroms/s) can possibly lead to higher Jc (5 MA/cm2)	Need better Jc in thicker films (roughness, sec. Phases, texture need to be improved)	Better substrates	
Scale up for higher rate	1 micron/min possible, but low Jc; abandoning LPE for now	Array of PED sources ; 13 * 2 array built in Germany	6000 km/yr possible at 100 Angstroms/s , L = 30 cm, w = 1m ; may possibly increase up to 1000 Angstroms/s	To demonstate high throughput with longer showerhead	6-stage CVD reactor set up ; only process used to produce 100 m YBCO ; 10 m/h demonstrated	4 m/h now ; Jipelec reactor has 45 cm2 area ; tape speed 40 m/h possible
Obstacles	high crystallinity ; Long oxygen anneal	Higher Jc ; more robust & reliable source	need O2 sensor	high Jc in thick films	Better substrates	
Advantages	High throughput at high temperature	1/10 cost of PLD ; small footprint ; better energy efficiency	high deposition rates (1000 Angstroms/s possible) ; Jc could be independent of thickness	High rate & unlimited deposition area	High throughput	Modular ; can easily add modules for high throughput
Research & Technological needs	Need architecture that yields high growth rate & high Jc		need to transfer technology to metal substrates - need to lower operating temp and/or high temp buffers	Further improvement in precursors		

Sneakare	Potorcon	Sathvamurthv	Show	Matenmoto	Avtua	Samhacivan
Deducts						
Butter layer	Srkucis	Lazzrzur	SLIIU3/CEUZ	BashU3, BazrU3	Laivinus	YZN
	on MgO IBAD/Ni-alloy on textured Ni-W	on textured Ni-W	on textured Ni	on SOE NiO/Ni	on textured Ni-W	on Ni or Ni-Cr13%
Process	ЫГД	solution	CCVD	PLD, MOD Solution	rf sputtering	reactive sputtering
Economics			non-vacuum, long			ECONO process;
		low-cost; good diffusion	length, low capital & materials cost, no post-		good diffusion barrier	<u>E</u> pitaxial <u>C</u> onversion to <u>O</u> xide via <u>N</u> itride
		barrrier for Ni	annealing	non-vacuum, high speed for Ni	for Ni	Oxidation
Speed		double-sided	5 h/m	1-10m/hr		1 m/min (feasible) but not demonstrated vet
Simplicity		single -buffer for PLD				
()) () () () () () () () () (single cap buffer	YBCO; CeO2 cap for TFA/BaF2				YZN to YSZ; CeO2 cap
Minimum buffer thickness					60 nm (300 nm for	70 nm YZN to produce 100 nm YSZ (volume
	50 nm (continuous)	60 nm	240nm (200nm, 40nm)		thick YBCO)	increases)
Keproducibility						
Processing issues	no chemical reaction with MgO IBAD layer or YBCO	BZO formation (CeO2 cap layer), substrate surface conditioning (sulfur), furnace design to emulate spin-coating		rough surface; Ra > 20 Jc on Ni-W is little nm; low Jc YBCO on Ni- lower than standard W	Jc on Ni-W is little lower than standard buffer architecture	O2 control
Current status		1 cm wide; up to 25 cm long	< 3m length			5 meter long buffers
YBCO performance				0.45 MA/cm2 (0.5 um) on PVD BaSnO3; 0.89	1.3 MA/cm2 on LMO (60 or 300 nm)/Ni-W; 0.9 MA/cm2 BaF2 YBCO/LMO/Gd2O3/	
				MA/cm2 (0.4 um) on PVD BaZrO3: 0.36	Ni; Ic 230 A/cm for LANL YBCO (1.65	1 MA/cm2 TFA or PLD YBCO on YSZ/NiCr:
	1.8 MA/cm2 (1.1um); 1.7 MA/cm2 (1.3 um)	lc of 80A.	1 MA/cm2 (0.2 um)	MA/cm2 on MOD BaZrO3	um)/LMO/LANL IBAD- 1MA/cm2 PLD MaO/Ni-allov YBCO/MaO/Til	1MA/cm2 PLD YBCO/MqO/TiN/Ni
What tech.?	PLD	el dip-coating		PLD	PLD	PLD
How long, wide, fast, and how good	short samples	25 cm long solution buffer	up to 3 meter; 1 cm wide		short samples	short samples
Near-term problems						
	depo I , tnickness to be optimized, Goal: Ic					
	> 100 A/cm on 1- meter SRO/IBAD	single -buffer for PLD YBCO; CeO2 cap for		need mechanical	large area LMO targets, increase	
	MgO/Ni-alloy	TFA/BaF2		polishing	throughput	

Characterization of Coated Conductors Session Summary

- A) Non-destructive quality control
 - 1) Process monitoring

For this purpose, the applications of Raman and Auger spectroscopy techniques were presented. The former is for detecting defects, such as antisite and oxygen deficiency, in the finished YBCO tapes while the latter is for the reel-to-reel detection of S coverage on the surface of RABiT-Ni substrates. This is needed to ensure the epitaxial deposition of CeO_2 or Y_2O_3 seed layers on Ni. Also, the former was being developed for in situ monitoring of YBCO formation. If this is accomplished, this will be very valuable for YBCO long tape production, which employs, for example, MOCVD for YBCO deposition.

2) Local J_c distribution

Possible use of magneto-optical imaging of J_c distribution was proposed for the reel-to-reel detection of low J_c regions of long tape. However, a better use of this technique is likely to be in conjunction with a standard reel-to-reel I_c measurement of superconducting tapes by transport currents to examine only the "bad" spots of the tapes in detail. Such I_c measurements are already being used for quality control of Bi2223/Ag tapes.

- B) TEM
 - The importance of TEM in revealing the role of the interfacial reaction in the epitaxial YBCO nucleation as well as the retainment of the c-axis orientation during the growth was pointed out. Also, the in- and out-of plane local misorientations among the grains can be nicely determined by the use of selected area diffraction technique as well as dark field imaging in TEM. However, the most important use of TEM is to identify and separate the process and the materials related microstructures, and then one can relate the microstructures and the properties with the processing variables.
- C) Electromagnetic Properties:
 - 1) Electro/thermal stability

As the critical currents of the tapes become increasingly large, the so-far neglected investigation of the cryo-stability of the coated conductors will become an important issue. At this moment, a good theoretical modeling is badly needed to assist better understanding of the limited available experimental results.

 dc critical currents and ac loss characterization and modeling. Very nice models of dc critical currents and ac losses were presented. The next step needed is to develop the identification of the microstructural defects, which lead to the modeled dc or ac loss behaviors.

Organization	Sinha Southwire	Barnes Air Force	Ishiyama Waseda Univ.	Kashima Chubu	Malazemoff AMSC	Neumueller Siemens	Shiohara ISTEC
Application	cable	generator transformer	SMES	cable	generator motor wind turbine gen	FCL	MagLev
Why coated Conductor cost		low ac loss, high T hiah Ic	reduce coil volume incr. refrigeration eff.		cables magn.processing	fast switching strong limiting	
т (К), В(Т)	72-77 self-field	4-5 Т, 20-77	incr. Stability 50 K, 10-T		-))	
Cost (\$/kA-m))	<50	not so cost-sensitive	<nbti< th=""><th><50</th><th><50</th><th><100</th><th>10 at 50 K</th></nbti<>	<50	<50	<100	10 at 50 K
I (A/cm); maximum I? 50 min	50 min	20 to 300 (DC) 1 MA	1 to 10 kA (50 tapes) 12 coils (toroid)	Je=0.07 MA min.		100 A/cm	40 kA/cm ² at 5T, 50 K
width (mm)	<mark>3 to 5</mark> 0 17 0.0			3 to 4		10 mm	
thickness (mm)	0.15-0.2					0.2	
Length (m) 200 Mechanical Properties higher than BSCCO	200 higher than BSCCO	2000		300-500 1.2 E6 A/cm ²	40	100 higher than BSCCO	1000 5CCO
<mark>ac losses</mark> joint resistance		generator: <100 W/MW				NA	
needs		withstand 15,000 rpm 2-5 MVV 100 A/turn L (2006-2010): 1000 km 2011-2015: 5000 km	(need transposed cable)	survive short-circuit 31.5 A cable length 150-200 m	survive short-circuit refrigeration 50-55K 31.5 A cable length 150-200 m	high Voltage per length	high thermal conduct. n>20